

# MAS836 – Sensor Technologies for Interactive Environments



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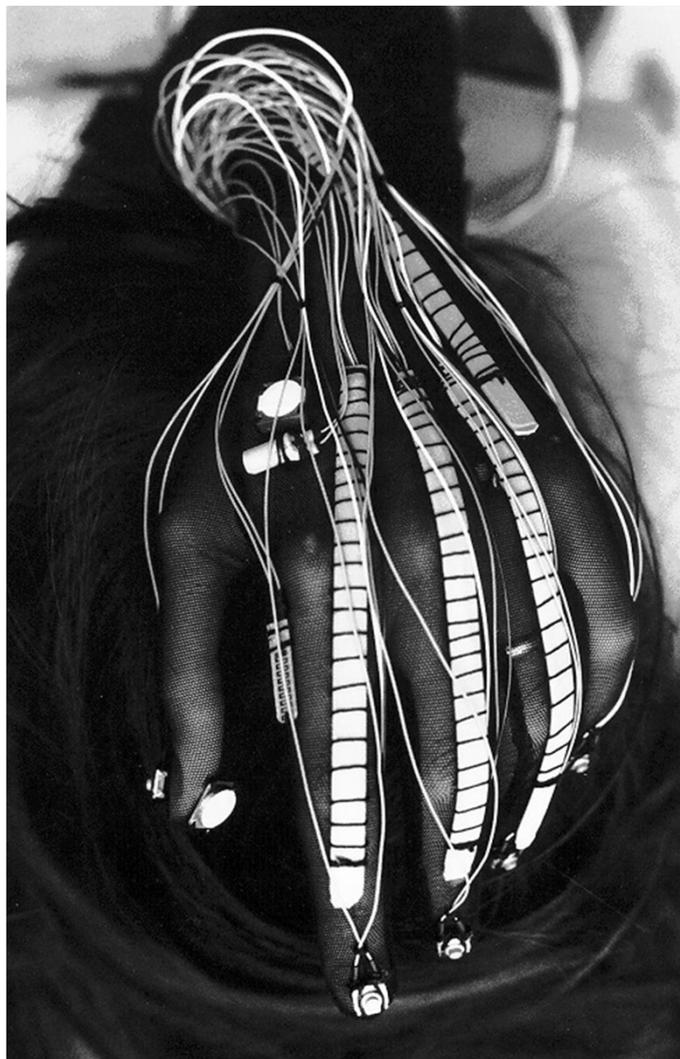
## *Lecture 5 – Pressure Sensors Pt. 2 and Piezoelectrics*

# Some FSR-Bendy-Sensor Gloves



Photo courtesy of [Tim Deering](#) on Flickr. CC-BY-NC

*Mattel's Power Glove  
1989*



Courtesy of Laetitia Sonami. Used with permission.

*Laetitia Sonami's Lady's Glove  
(STEIM, 1997)*



The 22-sensor CyberGlove has three flexion sensors per finger, four abduction sensors, a palm-arch sensor, and sensors to measure flexion and abduction. Each sensor is extremely thin and flexible being virtually undetectable in the lightweight elastic glove.

Courtesy of CyberGlove. Used with permission.

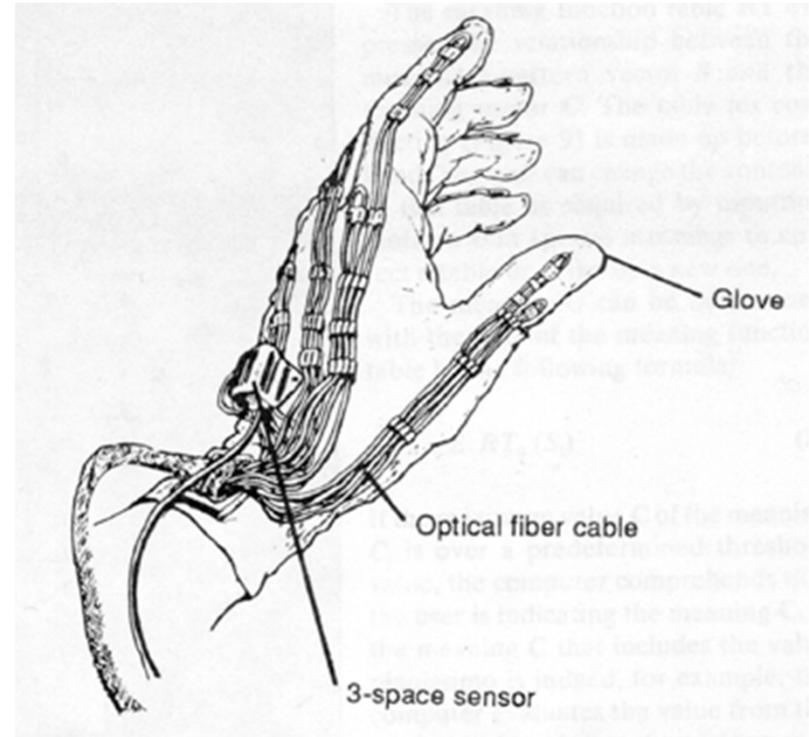
*Immersion's Cyber Glove*

# Data Gloves



5DT Data Glove 16

Black stretch lycra  
 Minimum dynamic  
 range is 8 bits.  
 Fiber optics based  
 14 Sensors in total  
 2 Sensors per finger. Abduction sensors  
 between fingers.



- Abraded-cladding fiber optic bend sensor in the Data Glove

Courtesy of 5DT Inc. Used with permission.

# Data Glove by Tom Zimmerman (VPL)

U.S. Patent

Jun. 26, 1990

4,937,444

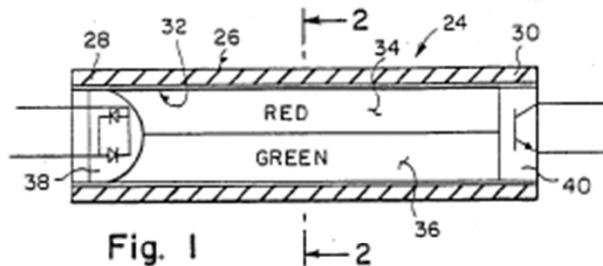


Fig. 1

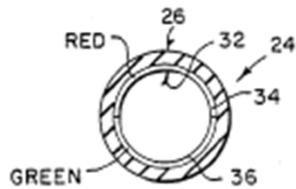


Fig. 2

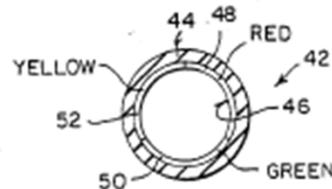


Fig. 2A

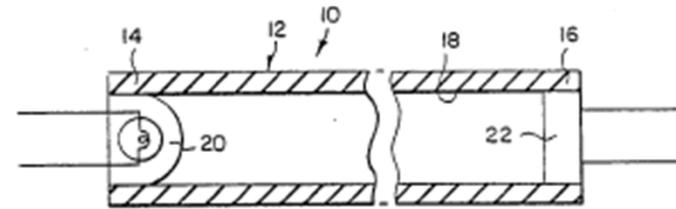


Fig. 3

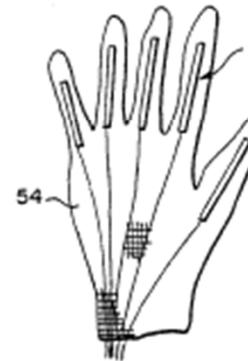


Fig. 4



Fig. 5

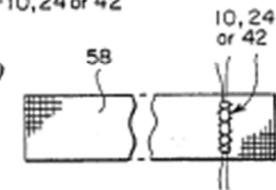
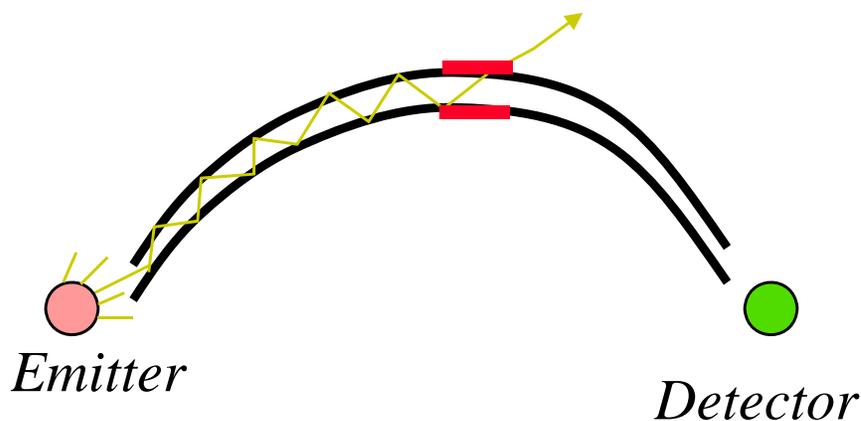


Fig. 6



- Cladding of a Graded Index Optical Fiber is abraded at point where sensitivity is desired
- When fiber bent, light leaks out as a function of bend angle
  - Drop in signal at detector
- Patented by Tom Zimmerman (lab alum) at VPL in 1985 & 1990.

# Measurand's Shape Tape

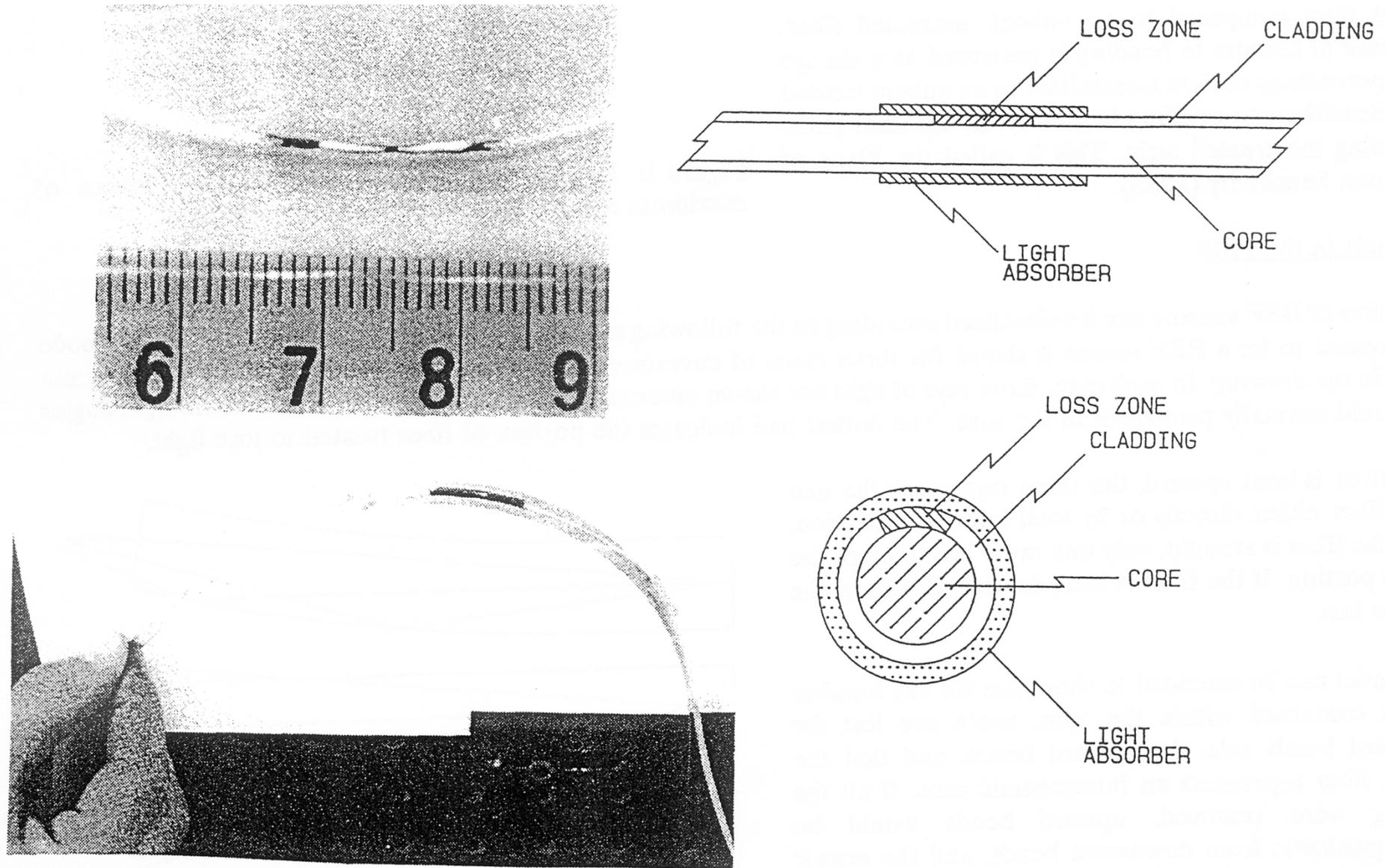
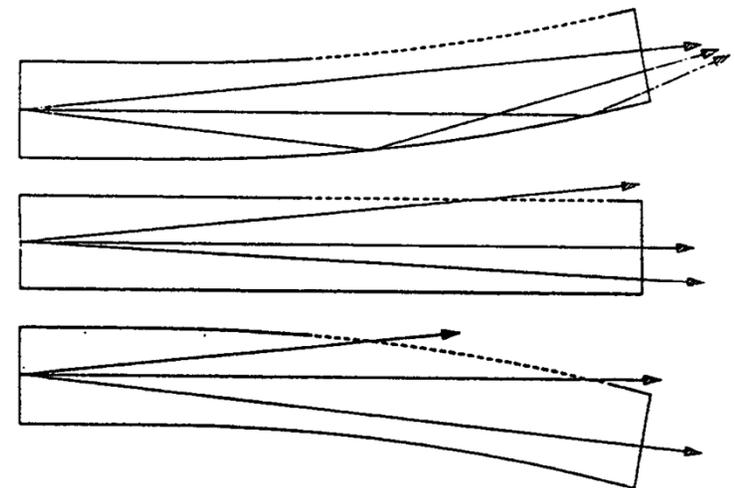
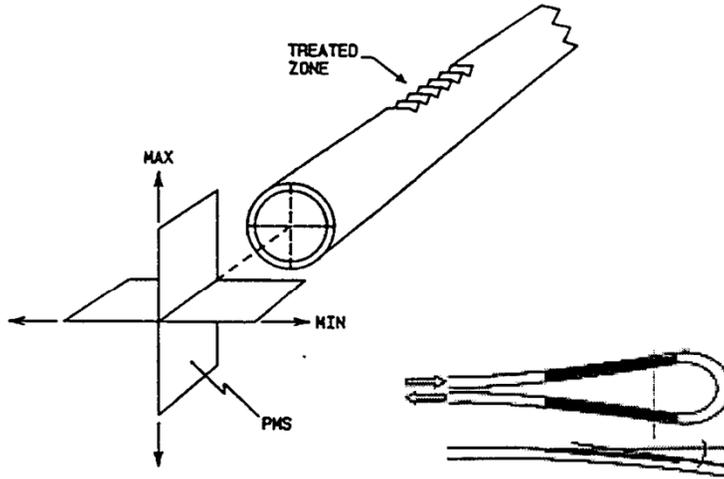
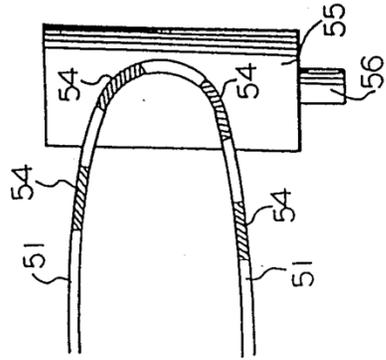


Figure 3: Examples of BEF sensors. Upper left: 200/230 micron BEF, coated with black epoxy over treated zone (scale marks: cm); Lower left: A BEF sensor attached to a thin metal substrate can be bent over large angles.; Right: construction of BEF sensor.

# Measurand's Shape Tape

The dotted line indicates the portion of fiber treated to lose light.

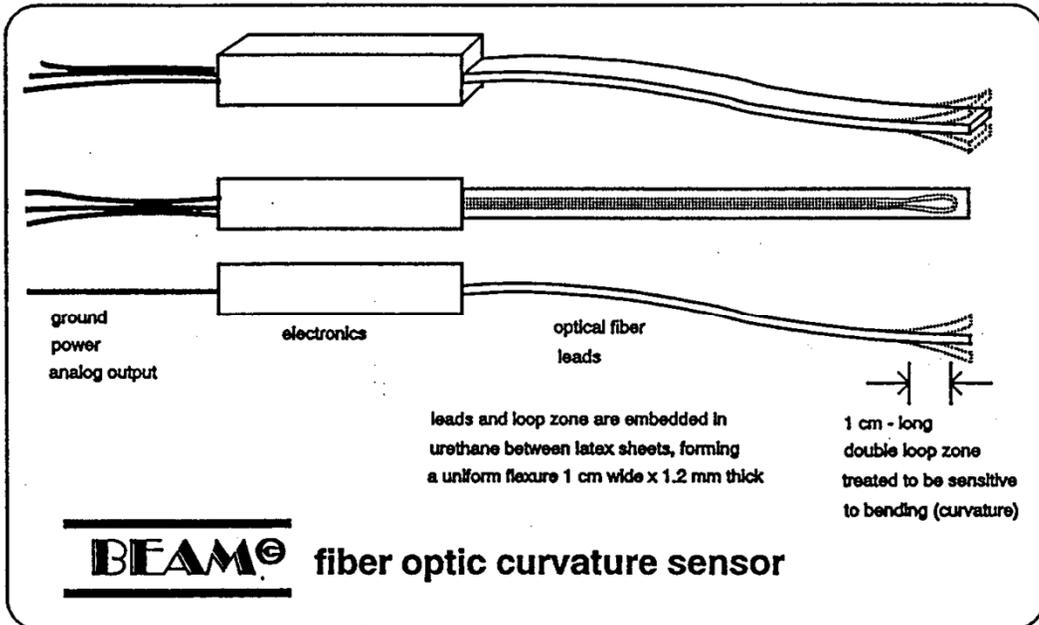


Can pixellate with an array of fibers, with treatment at different locations

Figure 1: Plastic fiber with a treated strip. Planes of maximum and minimum sensitivity are indicated.

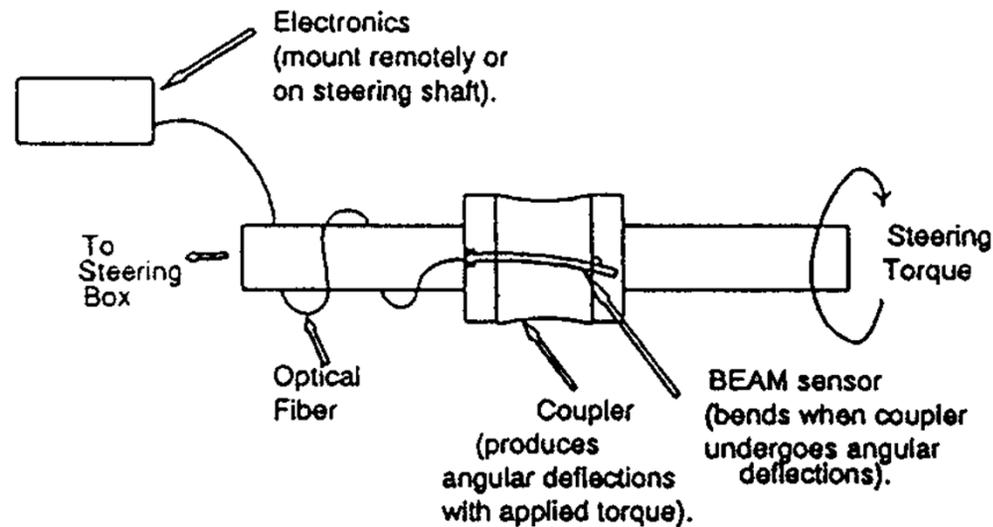
If the fiber is bent upward, the three rays reach the end of the fiber either directly or by total internal reflection. When the fiber is straight, only one ray is lost through the treated portion. If the fiber is bent downward, two of the rays are lost.

This model can be extended to show that for any number of rays contained within the core, more are lost for downward bends than for upward bends, and that the straight fiber represents an intermediate case. If all the cladding were removed, upward bends would be indistinguishable from downward bends, and the sensor would not be useful when straight, the most likely position for embedded fibers.



**BEAM** fiber optic curvature sensor

# How ShapeTape Measures Twist



*Bend fibers near center of strip  
Twist fibers near edges*

*Can also wrap fibers around center?*



Courtesy of Measurand. Used with permission.

**SHAPE TAPE™** uses paired loops to sense twist and bend along a ribbon substrate. In this case, sums and differences correspond to twist and bend, and there is no control loop used in ordinary applications.

# Shape Tape

## Characteristics, S1280CS multiplexed ShapeTape™

(Specifications will vary for other lengths, number of sensors, etc.)

Dimensions of tape: 1.3 x 13 x 1800 mm nominal

Dimensions of interface box: 16 x 54 x 168 mm nominal

Operating temperature: -20 to 50 deg c

Sensitive zone: outboard 480 mm contains 16 sensors arranged in 8 pairs

Sensor length: each sensor integrates curvature over a 60 mm portion of the sensitive zone

Sensor pair: each pair resolves bend and twist, using calibration constants

Calibration: Circle, twist, & flat poses yield stored calibration constants

Data: x,y,z and orientation at 16 or more points along sensitive zone, relative to inboard reference end

Calibrated Range of each sensor:  $\pm 40$  mm radius bend;  $\pm 22.8$  deg twist

Safe Bending radius:  $\pm 20$  mm radius

Spatial sampling limits: each monotonic (single polarity) curve requires two sensor lengths

Operating range for end of 'U' shape: two elliptical volumes, 160 x 250 mm each.

Endpoint accuracy within operating range and sampling limits: 1-3% of length is a reasonable expectation for positional errors; thus, for the first 100 mm of a tape, the error can be expected to be 1-3 mm, and if the tape is 1000 mm long, the error at the tip can be expected to be 10-30 mm.

Endpoint resolution: 0.3 mm rms, x,y, or z; 0.5 deg, roll, pitch, or yaw

Other locations on tape: errors reduce toward inboard reference end, within range and sampling limits

Maximum data acquisition speed: 110 Hz

Included: Wall mount power supply (60 Hz, 120VAC), serial cable, interface box, and tape

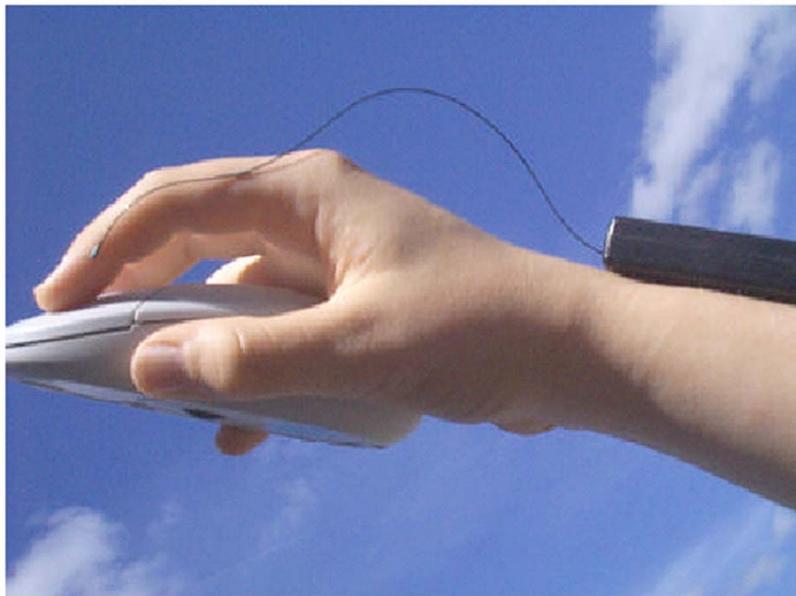
Courtesy of Measurand. Used with permission.

[http://www.youtube.com/v/ZMZr1jNDVGY&color1=0xb1b1b1&color2=0xcfcfcf&hl=en\\_US&feature=player\\_embedded&fs=1](http://www.youtube.com/v/ZMZr1jNDVGY&color1=0xb1b1b1&color2=0xcfcfcf&hl=en_US&feature=player_embedded&fs=1)

# Shape Tape Products

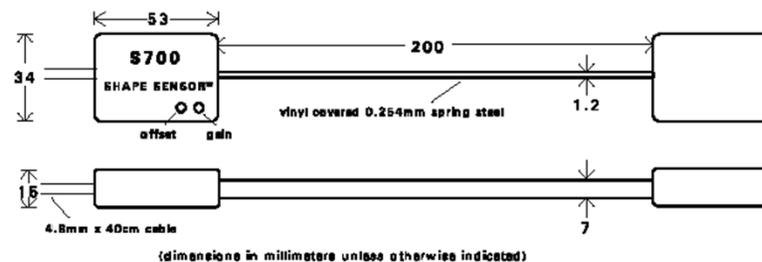
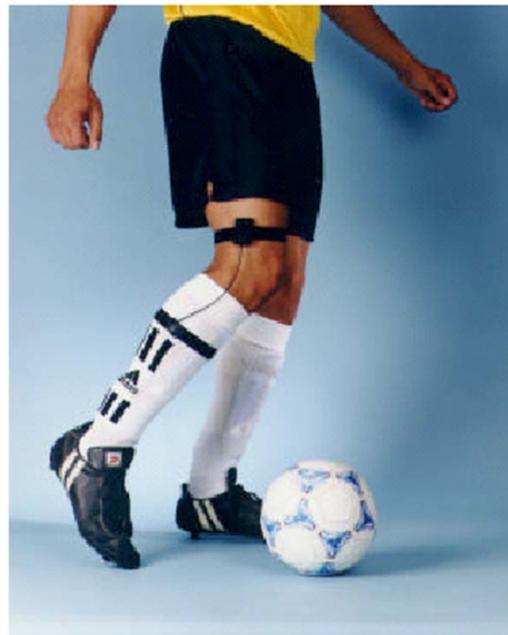
## S720 MINIATURE JOINT ANGLE SHAPE SENSOR™

Revision 20020912



## S700 JOINT ANGLE SHAPE SENSOR

Revision 20020912



Courtesy of Measurand. Used with permission.

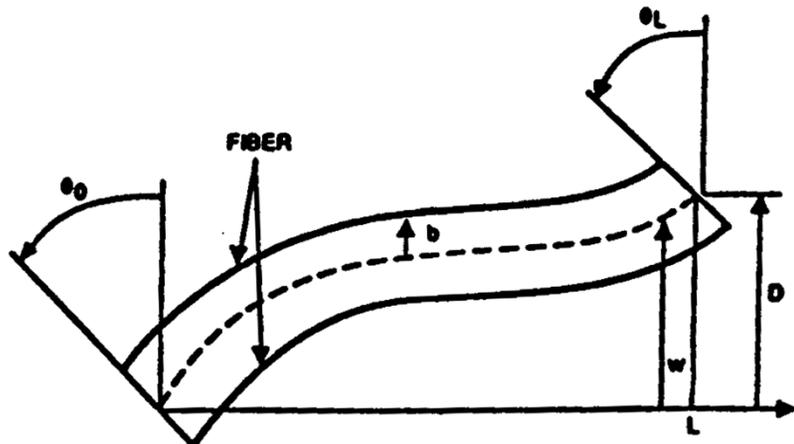
# AXIS - Alignment Transfer By Integrated Strain

**P** = sensor weighting (uniform)

**b(x)** = half diameter

**w''(x)** = rod curvature

**x** = distance along rod



OUTPUT OF INTEGRATING STRAIN SENSOR  
WITH WEIGHTINGS FUNCTION  $p(x)$

$$-\Delta L = \epsilon = \int_0^L P b(x) w''(x) dx$$

$$= P b(x) w'(x) \Big|_0^L - P b'(x) w(x) \Big|_0^L + \int_0^L P b''(x) w(x) dx$$

If  $b(x) = B$

$$\epsilon = P B [w'(L) - w'(0)] = P B (\theta_L - \theta_0) \text{ (ANGLE OUTPUT)}$$

If  $b(x) = K (1 - x/L)$

$$S = -K P w'(0) + K P/L [w(L) - w(0)]$$

$$= -K P (\theta_0 - D/L) \text{ (DISPLACEMENT OUTPUT)}$$

Courtesy of Draper Laboratory. Used with permission.

## Figure 1. AXIS Analysis.

- Invented by Len Wilk, Draper Lab
  - US Patent # 4,788,868 (1988)
- Output of a strain-measuring loop draped across a beam depends *only* on the difference between the angles of the ends

# Three-Angle measurements with twist

Note:  $D$  must be fairly small to avoid snapping measuring fiber or wire

As shown in Figure 2, a pair of fibers in the (nominally)  $y z$  plane will provide a measure of the relative rotation about the  $x$  axis (e.g. the pitch angle):

$$\Theta_p = \Delta L_y / D \quad (2)$$

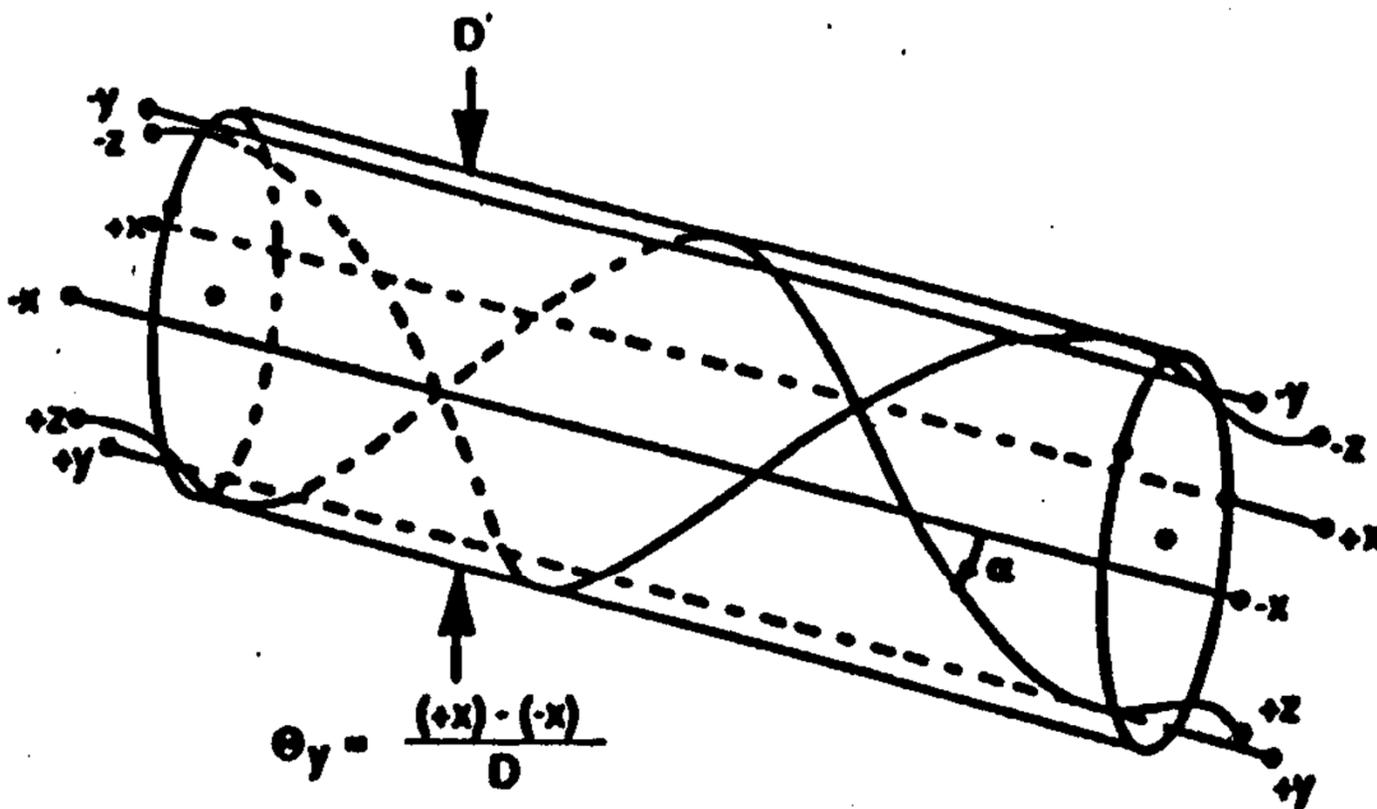
The pair of fibers in the (nominally)  $x z$  plane provide the yaw angle,

$$\Theta_y = \Delta L_x / D \quad (3)$$

while a clockwise helical fiber compared to a counterclockwise helical fiber provides the roll (twist) angle,

$$\Theta_r = \Delta L_z \sin \alpha / D \quad (4)$$

where  $\alpha$  is the helix angle,  $D$  is the diameter separating the pairs of fibers, and  $\Delta L$  is the difference in length between the fibers of a pair.



$$\Theta_y = \frac{(+x) - (-x)}{D}$$

$$\Theta_p = \frac{(+y) - (-y)}{D}$$

$$\Theta_r = \frac{(+z) - (-z)}{D} \sin \alpha$$



Some topological comments are in order. (1) The above configuration will provide the three angles independently given that the magnitude of the angles does not get too large (of order 30 degrees). (2) Bending and twisting that is constrained to one plane can be accommodated to large angles without topological limit. (3) Several rods can be joined in series: if the rods are joined at fixed right angles in cardinal directions, then the fiber pairs, rod to rod, can be joined so as to provide the proper angular transformations; if the rods are constrained to lie in cardinal planes, but at (fixed) arbitrary angles in these planes, and a double set of fibers implemented, the double pairs of fibers can be proportionally combined for proper transformations; with a triple set of fibers, the rods can be at any arbitrary fixed angles, and proportional combinations among the fiber pairs will provide the correct transformations.

- Helical windings provide measurement of twist

# Measurement of displacement with weighting

$$\epsilon = -KBw'{}^{(0)} + (w(L) - w(0)) = -KB(\theta_0 + D/L)$$

# AXIS Interferometric Readout

Thus, we see that angle and displacement of two reference points can be measured by integrating strain sensors. In the case of an optical fiber, the optical phase shift as a function of strain is given by the photoelastic effect

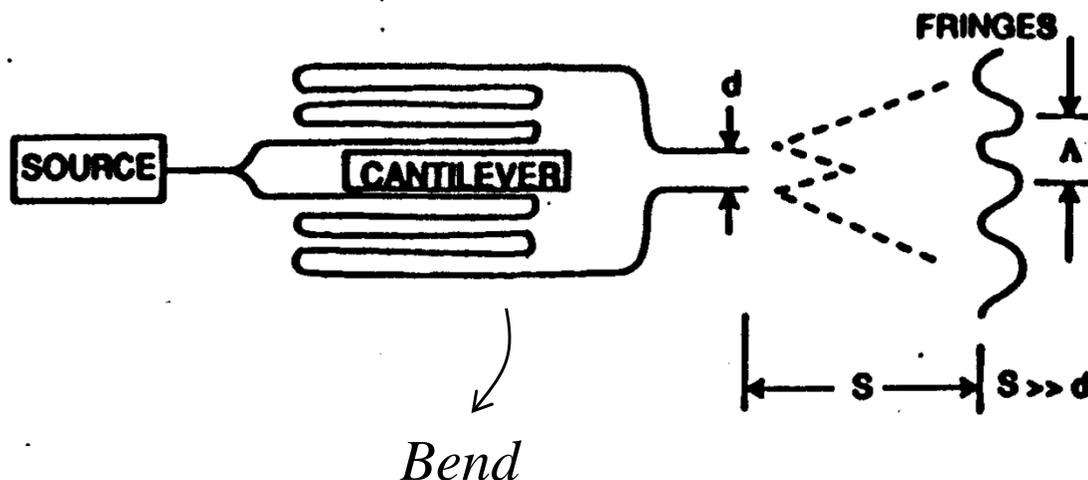
$$\phi(\epsilon) = knL(1 + \epsilon) - \frac{kn^3L}{2}(\rho_{12} - \nu(\rho_{11} + \rho_{12}))\epsilon \quad (5)$$

where  $k = 2\pi/\lambda$ ,  $n$  is the refractive index,  $\nu$  is Poisson's ratio, and  $\rho_{11}$  and  $\rho_{12}$  are the photoelastic constants. The cable would be instrumented with pairs of integrating strain sensors on opposite sides of the cable, operating in a differential mode.

Results in an arcsecond of deflection per fringe

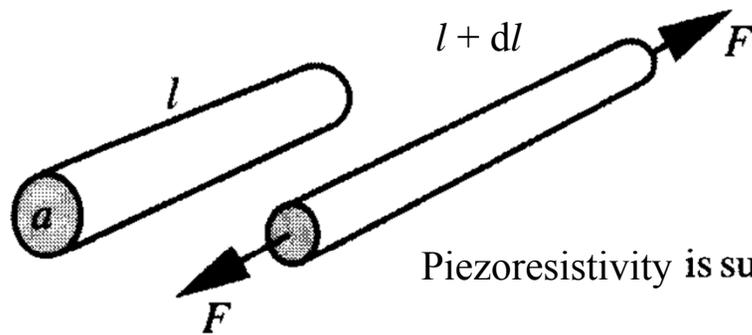
Differential measurement!

## Single-Axis Interferometer Schematic



Courtesy of Draper Laboratory. Used with permission.

# Resistive Wire Strain Detection



**Fig. 3.19.** Strain changes the geometry of a conductor and its resistance.

Piezoresistivity is successfully employed in sensors which are responsive to stress,  $\sigma$ :

$$\sigma = \frac{F}{a} = E \frac{dl}{l}, \quad \leftarrow \text{Strain } (e = dl/l) \quad (3.60)$$

where  $E$  is Young's modulus of the material and  $F$  is the applied force. In this equation, the ratio  $dl/l = e$  is called *strain*, which is a normalized deformation of the material.

Figure 3.19 shows a cylindrical conductor (wire) stretched by applied force  $F$ . The volume  $v$  of the material stays constant while the length increases and the cross sectional area becomes smaller. As a result, Eq. (3.54) can be rewritten as

$$R = \frac{\rho}{v} l_2. \quad (3.61)$$

After differentiating, we can define sensitivity of resistance with respect to wire elongation:

It follows from this equation that the sensitivity becomes higher for the longer and thinner wires with a high specific resistance. Normalized incremental resistance of the strained wire is a linear function of strain,  $e$ , and it can be expressed as

$$\frac{dR}{R} = S_e e, \quad \leftarrow \text{Gauge Factor} \quad (3.63)$$

where  $S_e$  is known as the *gauge factor* or *sensitivity* of the strain gauge element. For metallic wires, it ranges from 2 to 6. It is much higher for semiconductor gauges; it is between 40 and 200.

Resistance  $R = \rho(l/a)$   
 Resistivity  $\rho$   
 Length over cross-sectional area  $l/a$

# Strain Gauge Patterns

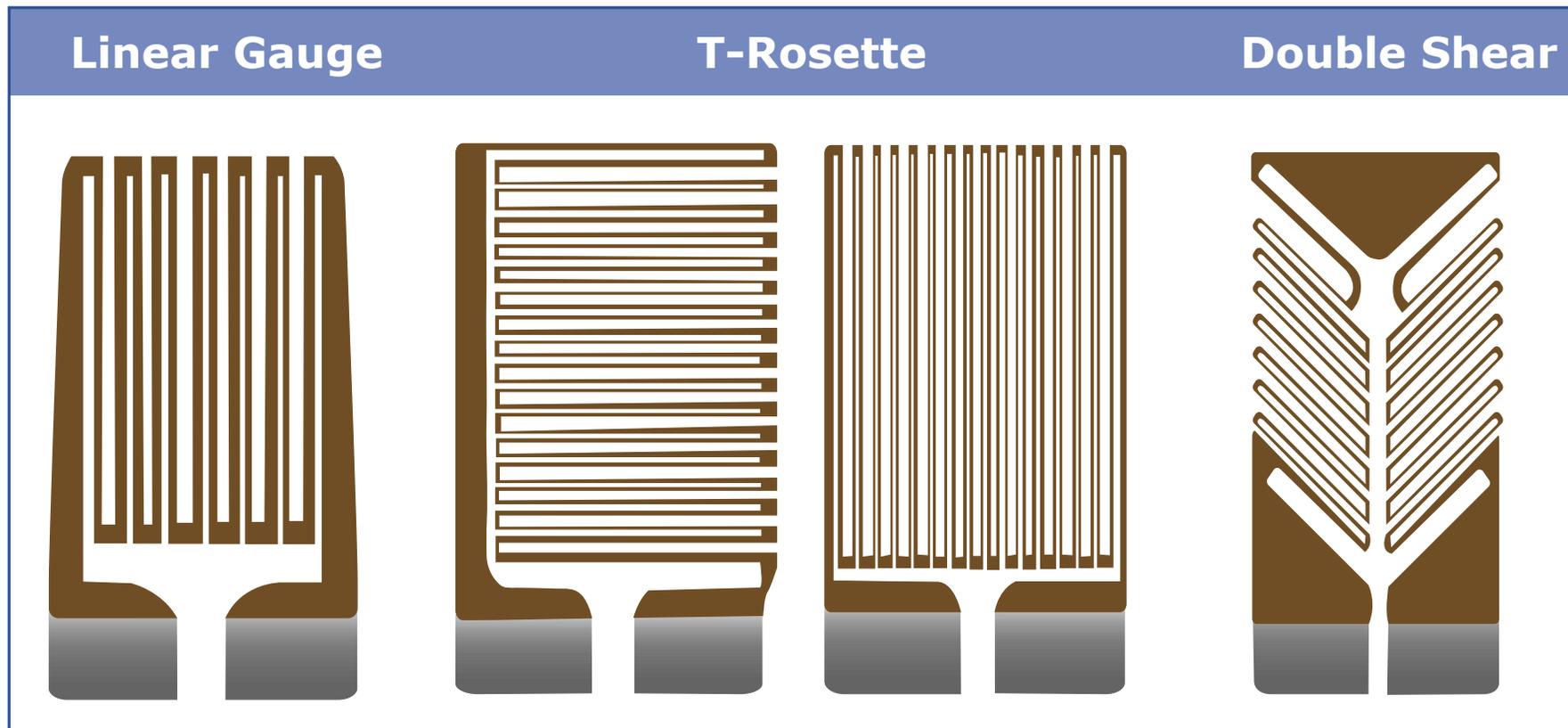
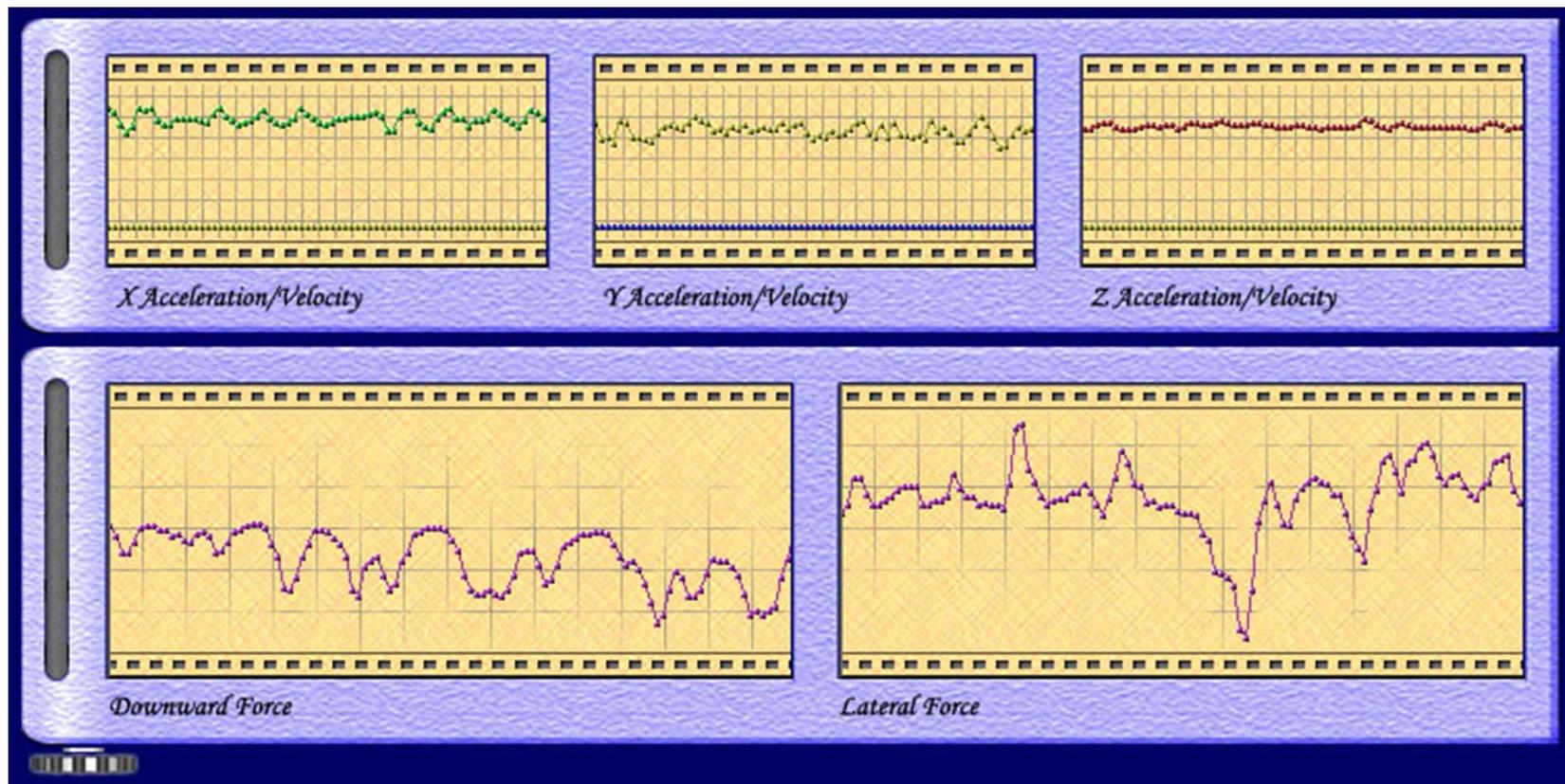
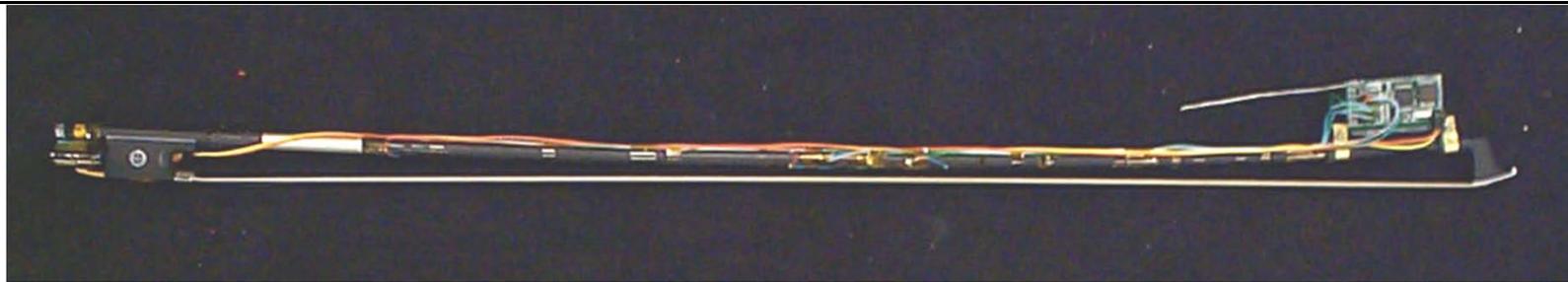


Image by MIT OpenCourseWare.

Strain Gauges want to be bonded onto a hard surface, so they can be forced into strain when the surface is deflected. Soft materials won't strain the gauge enough

# Current Work – Diana Young's wireless bow



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- Strain gauges on bow for bow bend (in x,y) and twist.
- Accelerometers for 3-axis motion
- Capacitive transmitters as before for position

# Load Cells



*Simple, “naked” load cell from Ohio State*

- Bond strain gauge to cantilevered beam
  - Force deflects beam, bends strain gauge, creates signal
- Can be quite accurate
  - Compensate temperature effects

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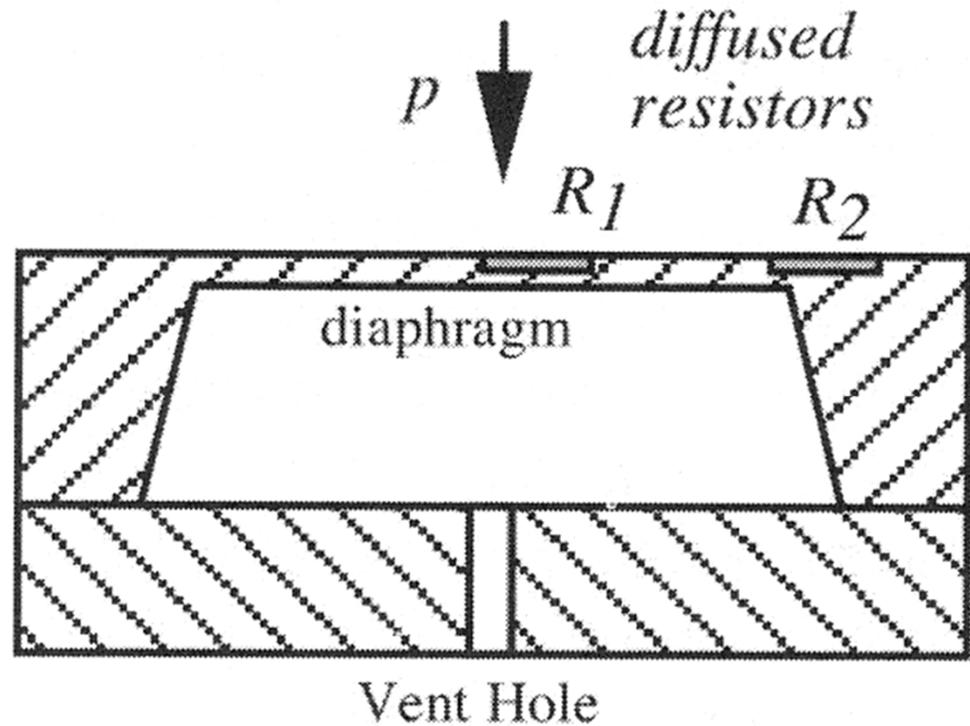
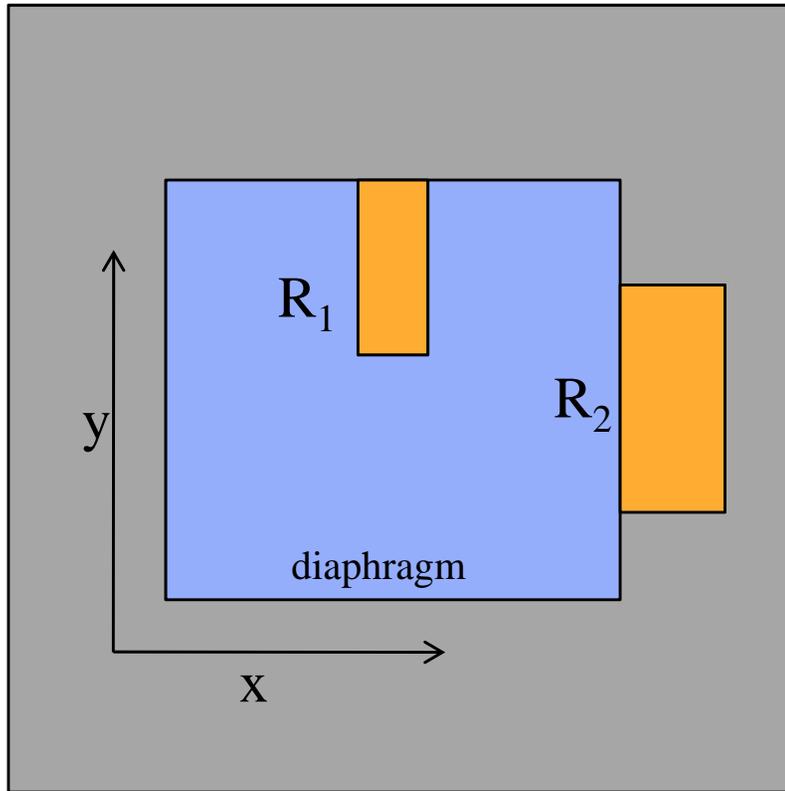
*20 Ton load cell for truck weight*



*Load Cell assortment from DHS*

# Silicon Pressure Sensors

Fig. 10.4. Position of piezoresistors on a silicon



- Piezoresistors diffused onto silicon at R1, R2
  - Boron doping typical...
- Piezoresistors couple into longitudinal & transverse stress
  - Coupling is opposite for each mode
- R1 and R2 essentially subtract in a half-bridge

where  $\pi_l$  and  $\pi_t$  are the piezoresistive coefficients in the longitudinal and transverse direction, respectively. Stresses in longitudinal and transverse directions are designated  $\sigma_l$  and  $\sigma_t$ . The  $\pi$  coefficients depend on the orientation of resistors on the silicon crystal. Thus, for  $p$ -type diffused resistor arranged in the (110) direction or an  $n$ -type silicon square diaphragm with (100) surface orientation as shown in Fig. 10.4, the coefficients are approximately denoted as [7]

$$\pi_l = -\pi_t = \frac{1}{2}\pi_{44}. \quad (10.11)$$

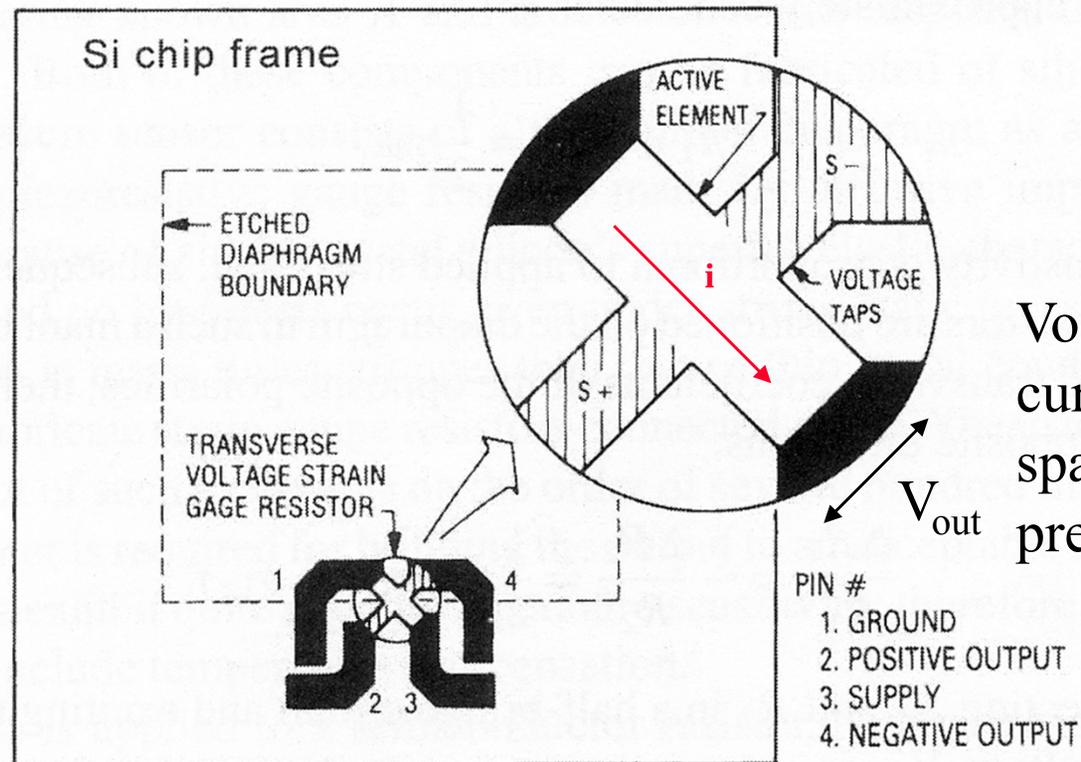
A change in resistivity is proportional to applied stress and, subsequently, to applied pressure. The resistors are positioned on the diaphragm in such a manner as to have the longitudinal and transverse coefficients of the opposite polarities; therefore, resistors change in the opposite directions:

$$\frac{\Delta R_1}{R_1} = -\frac{\Delta R_2}{R_2} = \frac{1}{2}\pi_{44}(\sigma_{1y} - \sigma_{1x}). \quad (10.12)$$

When connecting  $R_1$  and  $R_2$  in a half-bridge circuit and exciting the bridge with  $E$ , the output voltage  $V_{out}$  is

$$V_{out} = \frac{1}{4}E\pi_{44}(\sigma_{1y} - \sigma_{1x}). \quad (10.13)$$

# Motorola MPX Pressure Sensor



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- Pressure sets up electrical field in non-excited connections (hence voltage)
  - Analogous to Hall effect
  - Essentially already a bridge
  - Everything is on one substrate - simpler T compensation

# Pressure Sensors

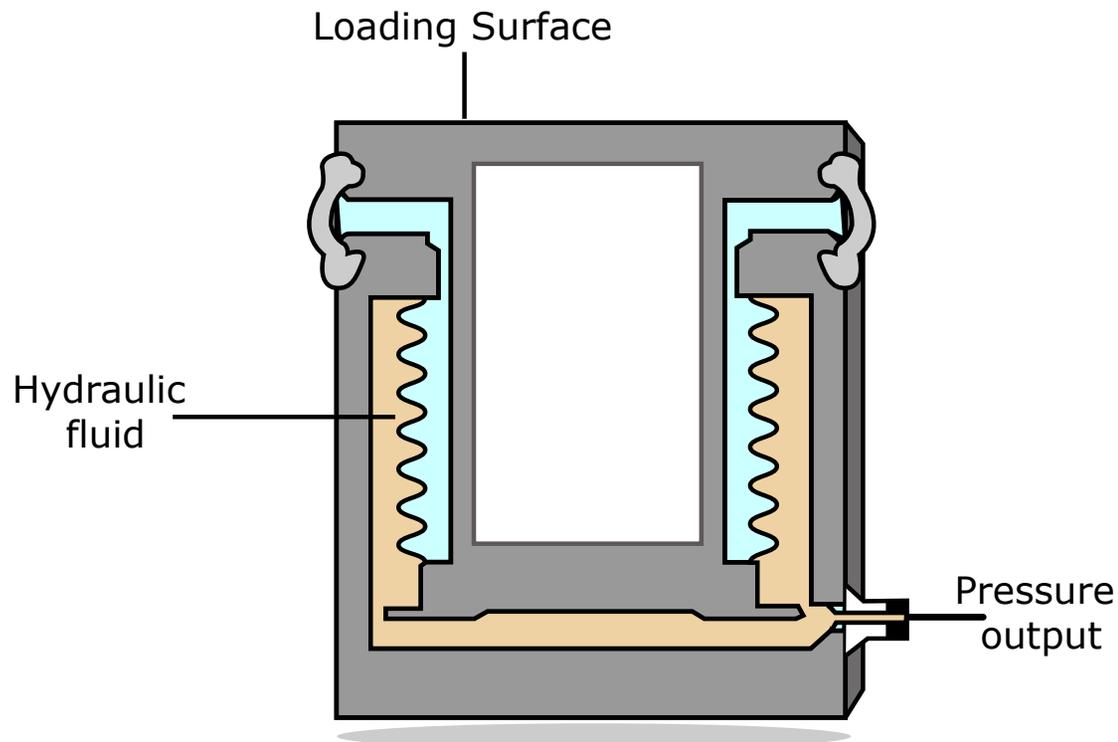


Image by MIT OpenCourseWare.

Photos of various pressure sensors removed due to copyright restrictions.

Hydraulic Load Cell

*Link to UW paper on elevators*

*Many manufacturers: Motorola, MSI, Silicon Designs...*

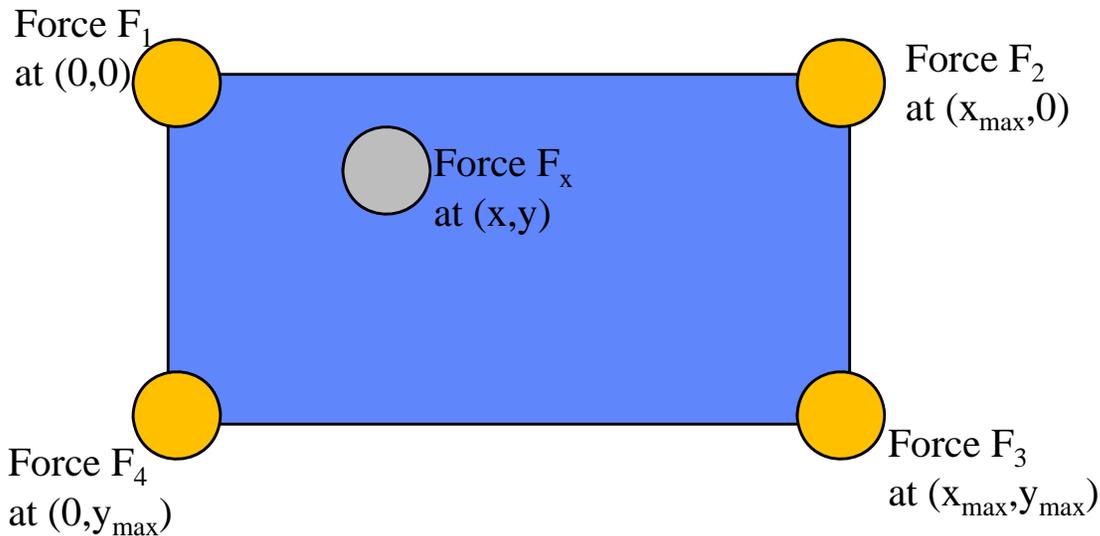
- Absolute and Differential (air or fluid) pressure
  - Back of diaphragm open or closed to the air/medium

# UW/Intel Wearable Monitoring

Graph removed due to copyright restrictions.

Brunette, W., Lester, J., Rea, A., and Borriello, G. 2005. Some sensor network elements for ubiquitous computing. In Proceedings of the 4th international Symposium on information Processing in Sensor Networks (Los Angeles, California, April 24 - 27, 2005). Information Processing In Sensor Networks. IEEE Press, Piscataway, NJ, 52.

# Force Balance Platform

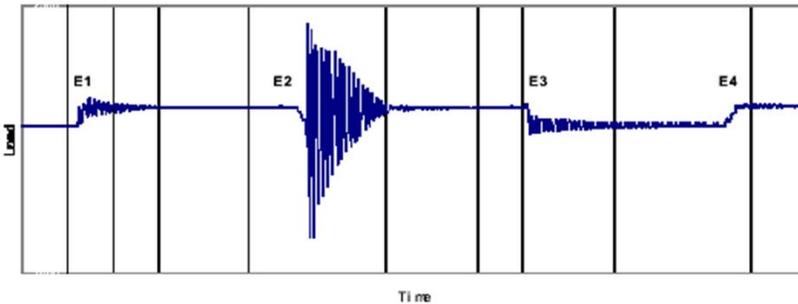


$$F_x = F_1 + F_2 + F_3 + F_4$$

$$F_{0x} = F_{01} + F_{02} + F_{03} + F_{04}$$

$$x = x_{max} \frac{(F_2 - F_{02}) + (F_3 - F_{03})}{(F_x - F_{0x})}$$

$$y = y_{max} \frac{(F_3 - F_{03}) + (F_4 - F_{04})}{(F_x - F_{0x})}$$



By looking at the dynamic pressure balance on the table, objects on the table can be identified by weight change and tracked by force balance. Ditto for people moving around the floor

*Albrecht Schmidt, et al., Ubicomp 2002*

[http://ubicomp.lancs.ac.uk/smart-its/Weight\\_Table/weight\\_table.html](http://ubicomp.lancs.ac.uk/smart-its/Weight_Table/weight_table.html)

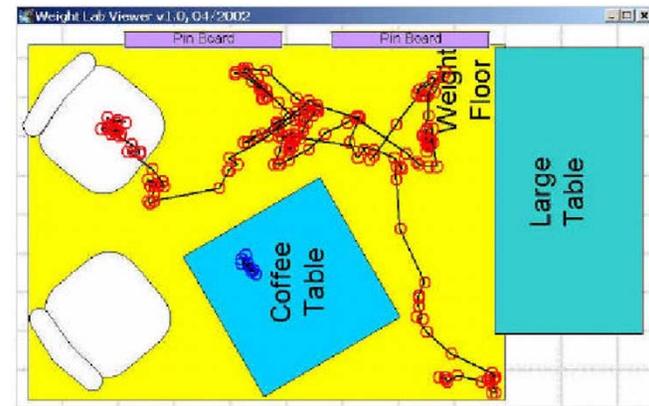


Fig. 8. Weight lab viewer showing a trace on the floor layout of the lab and also some interaction with the table (object put down).



# Piezoelectric References

Cover of “Piezoelectric  
Ceramics: Principles and  
Applications”, APC  
International, removed due to  
copyright restrictions.

- APC International
  - Piezoelectric Ceramics: Principles & Applications
- Websites:
  - MSI Tutorial, Piezo Systems Tutorial

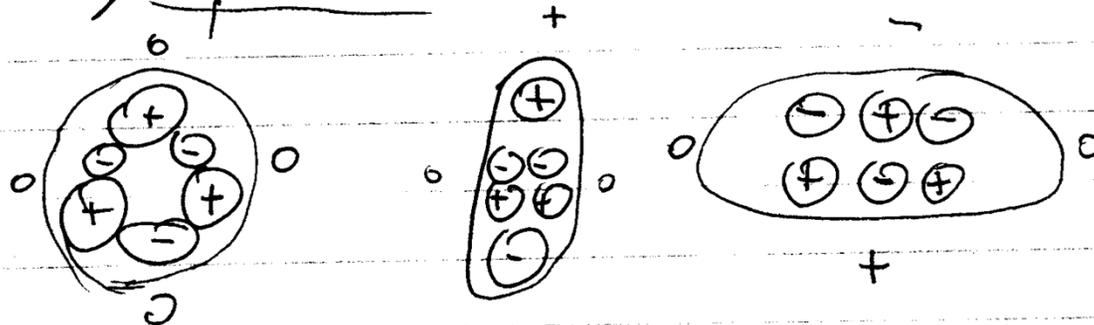
# Piezoelectrics

## Piezoelectrics

Measure dynamic force

Ferroelectrics

Deformations of unit cell produce charge  
 Crystals (quartz), Ceramics (PZT), Polymers (PVDF)   
 or Kytrac



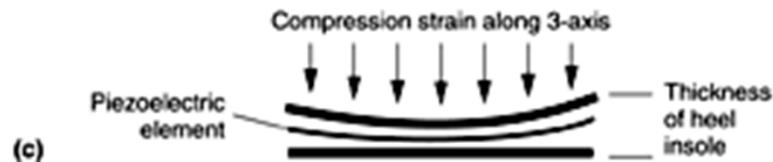
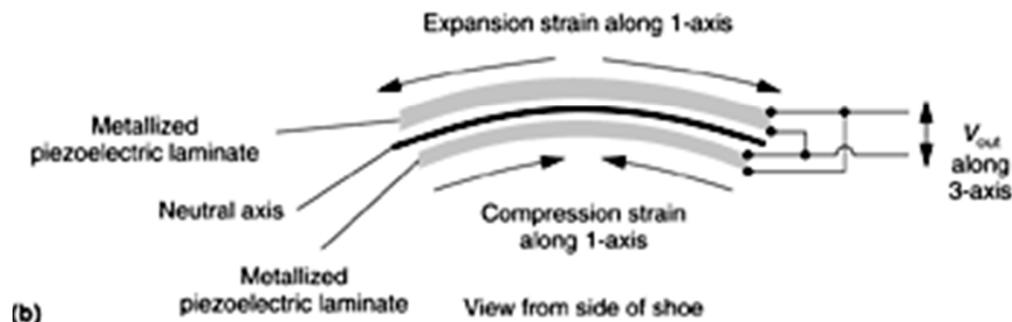
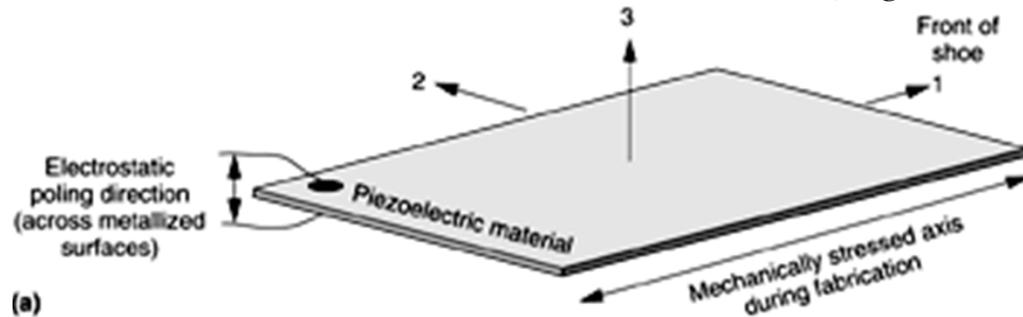
- Crystal lattice gives intrinsic poling
- Ceramics, Polymers need to be poled
  - $\vec{E}$  field, pulling (foil), Temp ( $\rightarrow$  cure)

→ Foil becomes "semicrystalline homo polymer"



# Piezo Axes under Strain

*Electrodes aluminized, silver inked, carbon (high strain)*



*Piezo Strain Coefficients:*

$d_{31}, d_{32}, d_{33}$  -> Coulombs/Newton (charge/force)

*Piezo Voltage Coefficients:*

$g_{31}, g_{32}, g_{33}$  -> Electric Field Strength/Pressure  
 ( $[V/m]/[N/m^2]$ )

$$g_{mn} = d_{mn}/\epsilon$$

*Note: Connected here in parallel for power generation*

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*Capacitor - charge collection electrodes along 3 axis*

*In polling process, material heated, electric field applied along 3, strain along 1*

# Voltage from Strain

Crystal, Resonator  
hard, resonant  
w. high  $\rho$

Foil soft, inductively  
Broadband  $\rightarrow$  GHz

High dynamic range  
(Foil,  $10^{-8}$  -  $10^6$  psi)

$$D = \frac{\Delta Q}{A} = d_{3n} \times \sigma_n$$

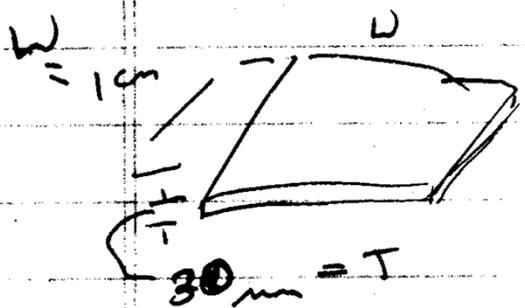
Charge displaced / Charge sens.  $\rightarrow$  Stress along n

$$V = g_{3n} \times \sigma_n \times t$$

Thickness

$$\text{Stress} = \frac{\text{Force}}{\text{Area}}$$

3-3 mode



$$V = g_{33} \times \left( \frac{F}{w^2} \right) \times t$$

Force in 3-3

$$g_{33} \left( \frac{F}{w^2} \right) t$$

Foil core  
in Shear  
(9-110mm)  
+  
Wire

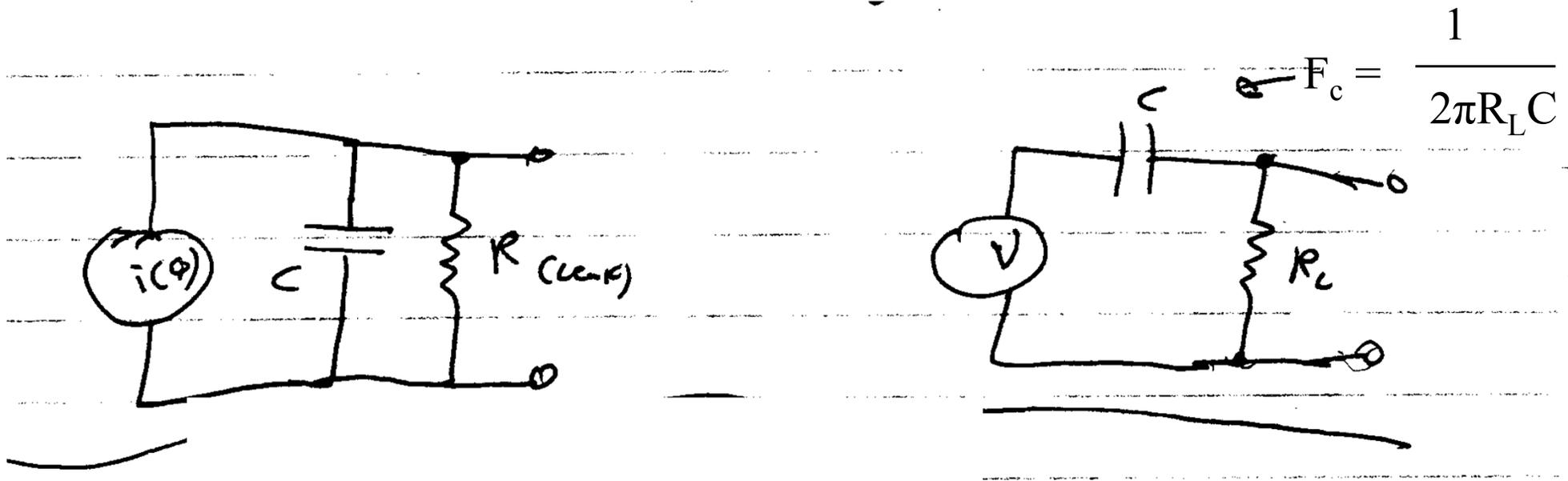
Force in 3-1 *t is small and w is big*

$$V = g_{31} \times \left( \frac{F}{wt} \right) \times t = g_{31} \left( \frac{F}{w} \right)$$

Force/cm-mm

3-1 mode generally much more responsive than 3-3

# Equivalent Circuits

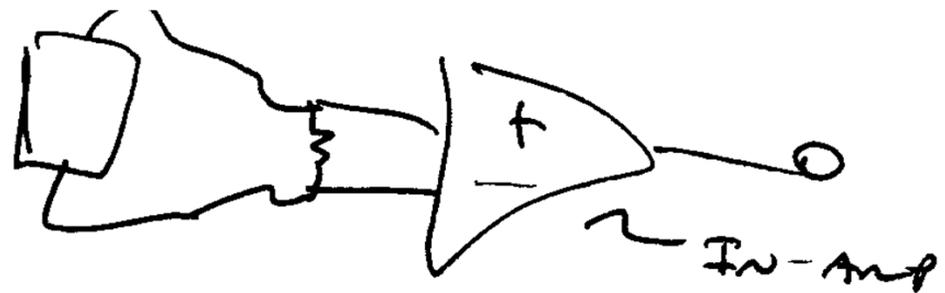
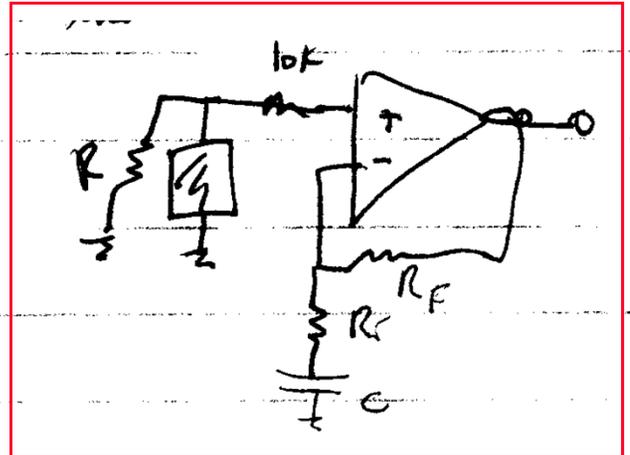
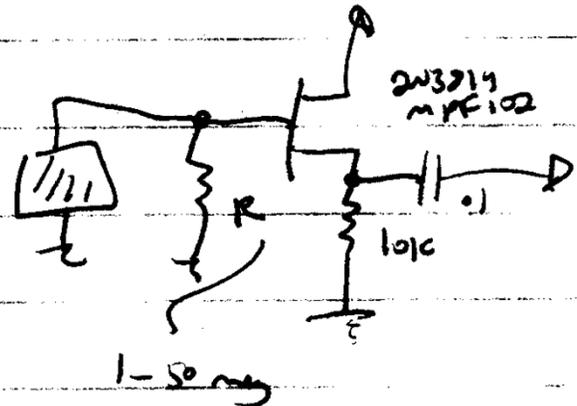


*High and reactive Impedance!*

*Capacitive Signal Source*

# Circuits, etc.

Connecting  
Pressure  
⇒ Volts



*Some use charge-sensitive (integrating or transimpedance) amplifiers - e.g., to approximate steady-state pressure*

*I tend to use high-impedance amplifiers for piezoelectric elements*



# Piezo Foil (PVDF)

Photos of piezo film sensors removed due to copyright restrictions.  
See: [Measurement Specialties](#).

# Applications

PVDF uses

→ Rugged, easily interfaced, nice signals

~ Dynamic Pressure

[Feet, fingers, furniture, shoes...]

⇒ Acoustic pickup [Suspension...]

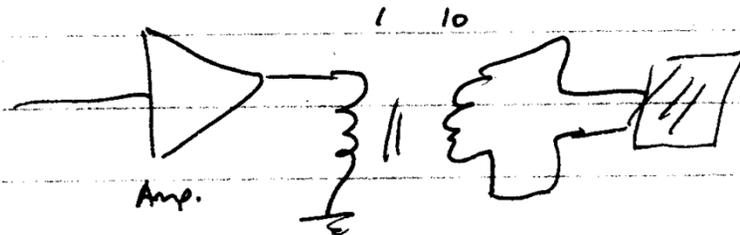
⇒ Sonar

⇒ Distributed Transducer / Array

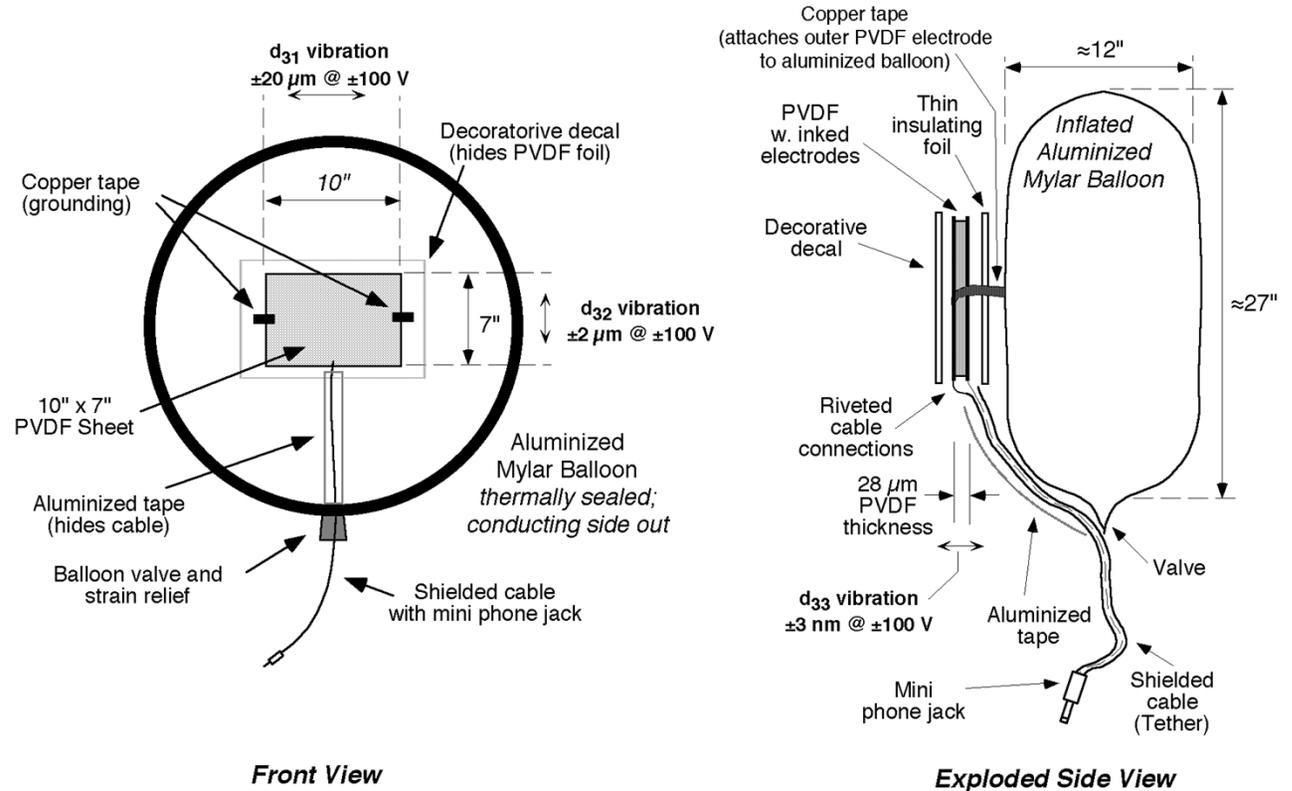
⇒ Reciprocal ~ Actuator



→ Morph

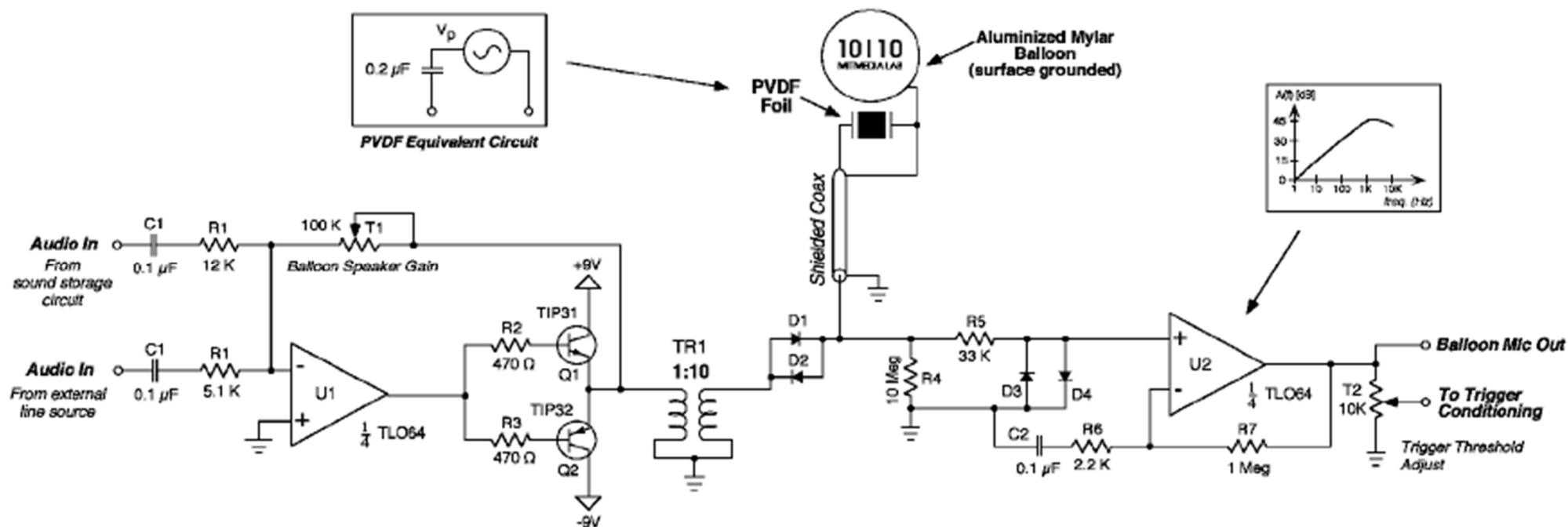


# 1995 - Interactive Audio Media



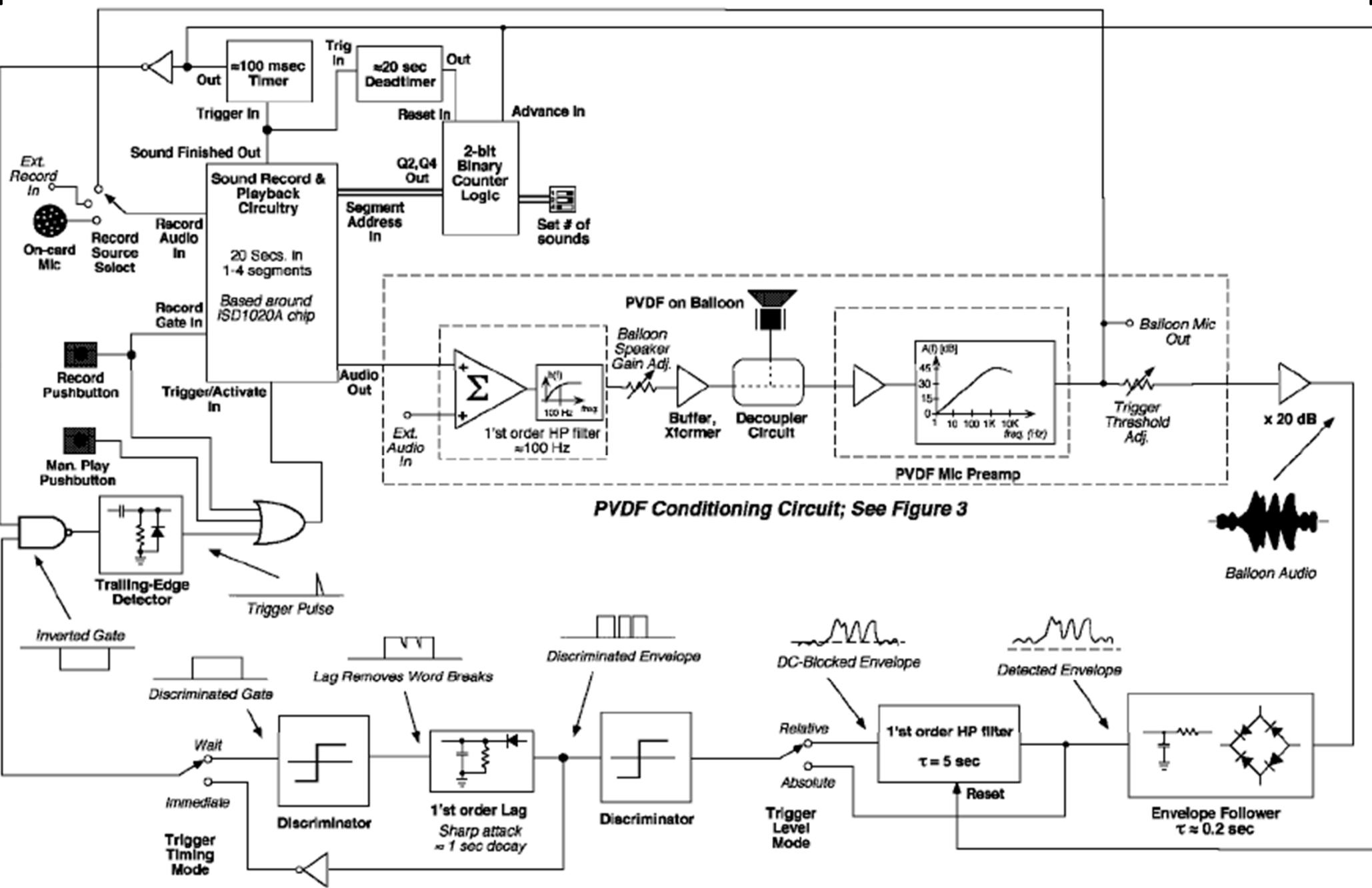
- PVDF strip laminated onto balloon surface forms speaker and microphone
- Simple electronics enable very simple “behavior”
- All over Media Lab for 10'th birthday (60 made)

# Balloon Driver/Buffer

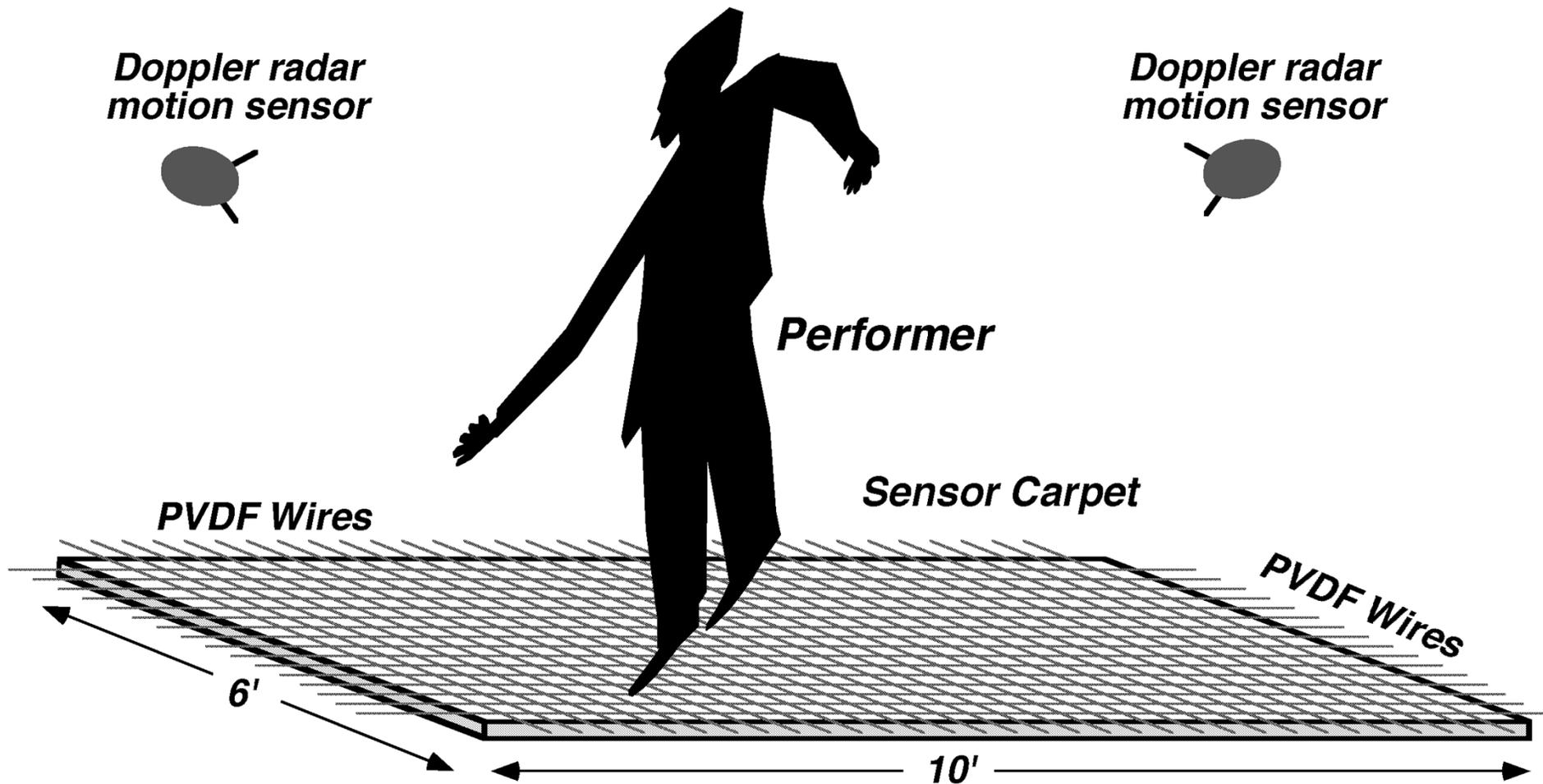


*Transformer output boost, diode-based TR switch, and HP input response*

# All in Analog(!)

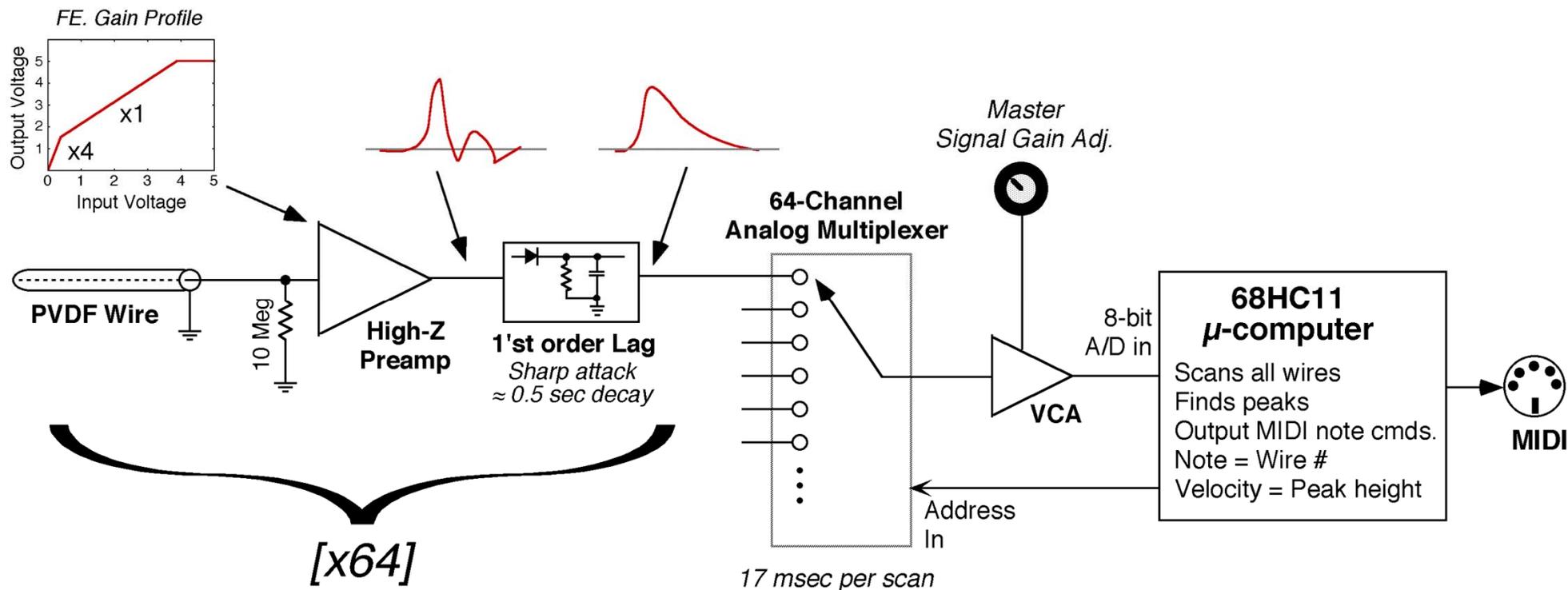


# The Magic Carpet



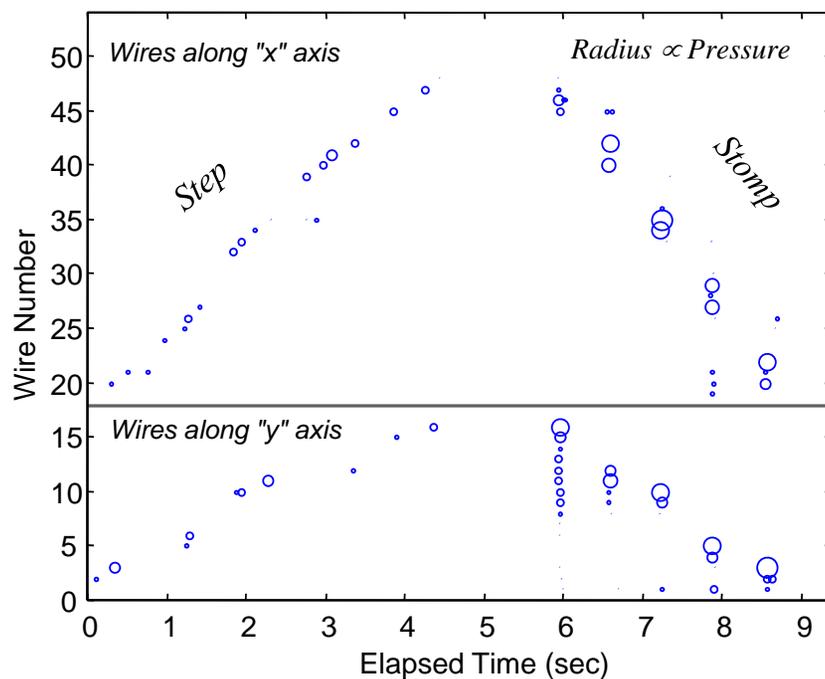
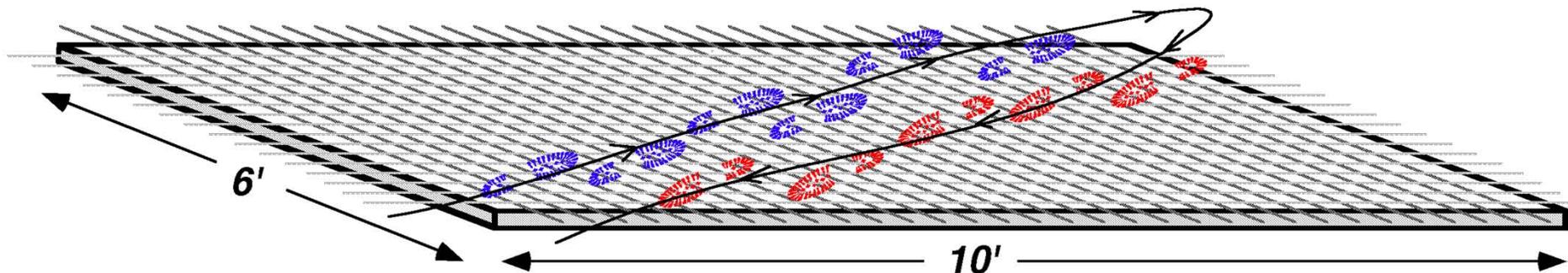
- Foot position, dynamic pressure captured by 4" grid of piezoelectric wire
- Pair of orthogonal Doppler radars measure upper body motion
- Not currently in the Brain Opera...

# Sensing in the Carpet

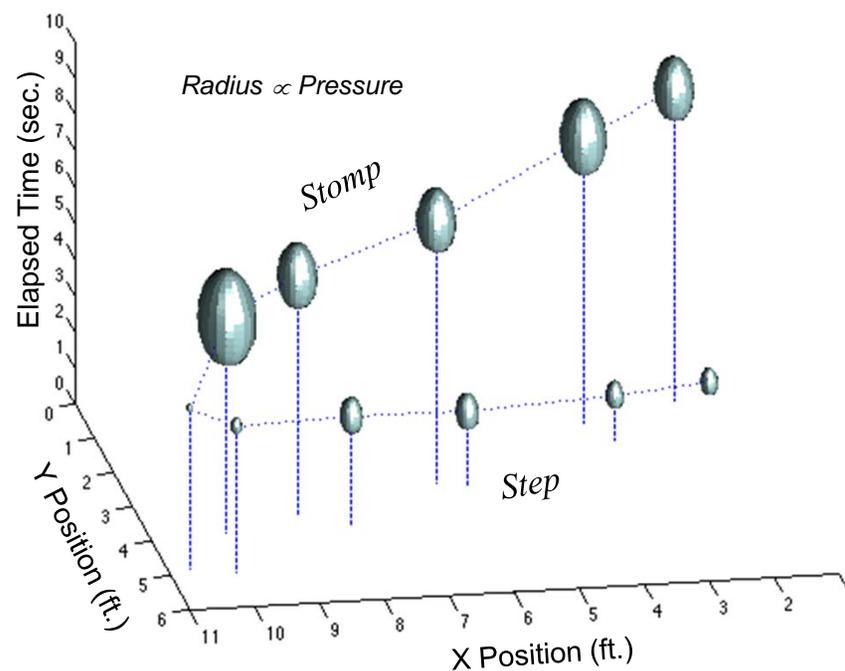


- Up to 64 PVDF wires are sampled at 60 Hz
- MIDI note events generated at every peak
- Simple electronics...

# Carpet Data Analysis



Raw data from carpet wires



Data after time clustering

# Smart Flooring at the MIT Museum

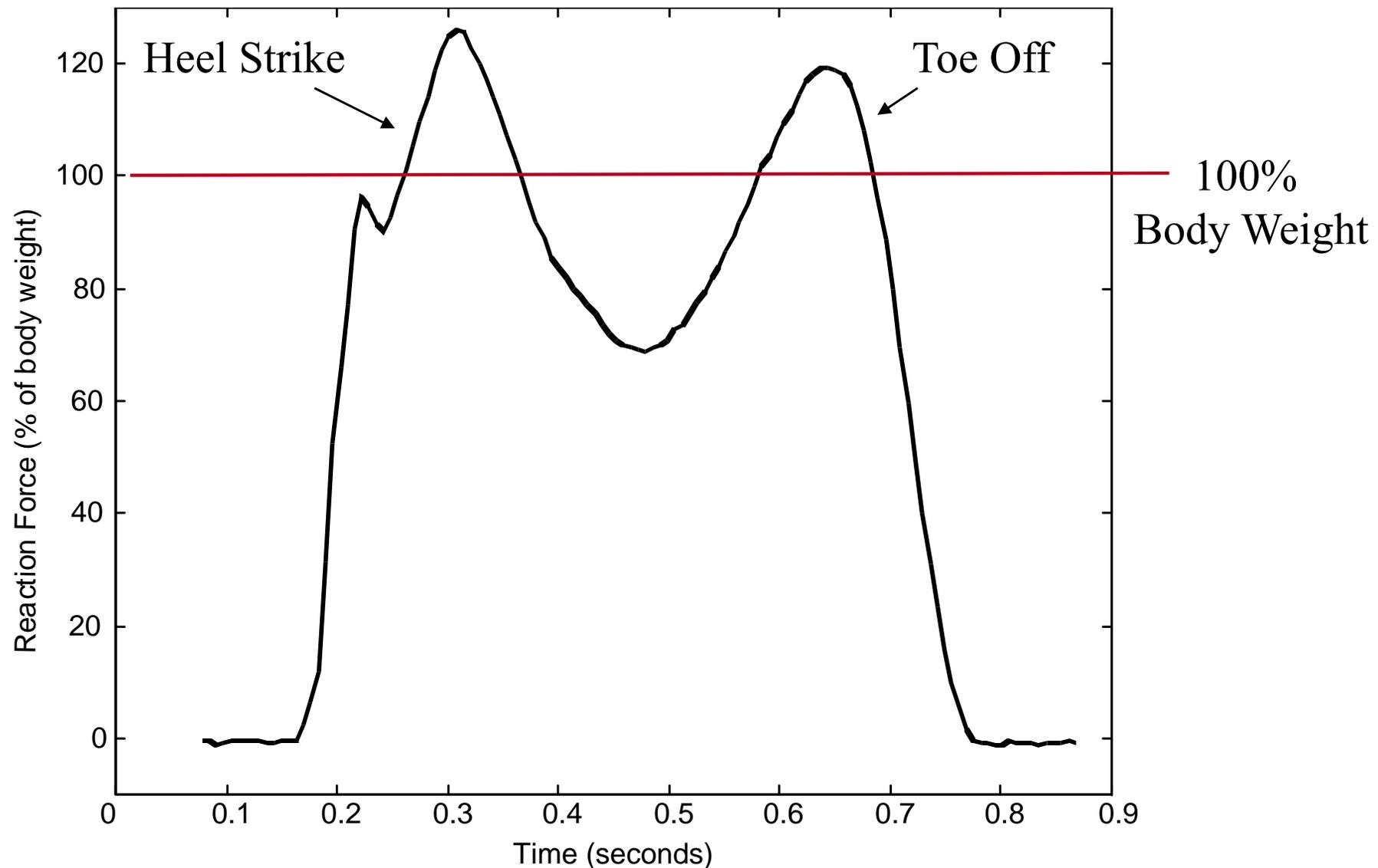


## Stomping Ground

*Permanent installation at the MIT Museum, opened 4/30/02*

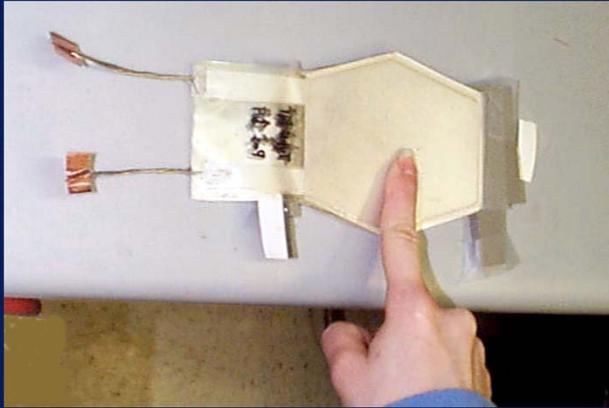
*Collaboration with John Maeda's A&C Group (graphics)*

# Heel Strike



- Force at heel strike and toe off exceeds 100%
  - Heel can compress by 1 cm – Watts possible?

# Power Harvesting Insoles - 1998



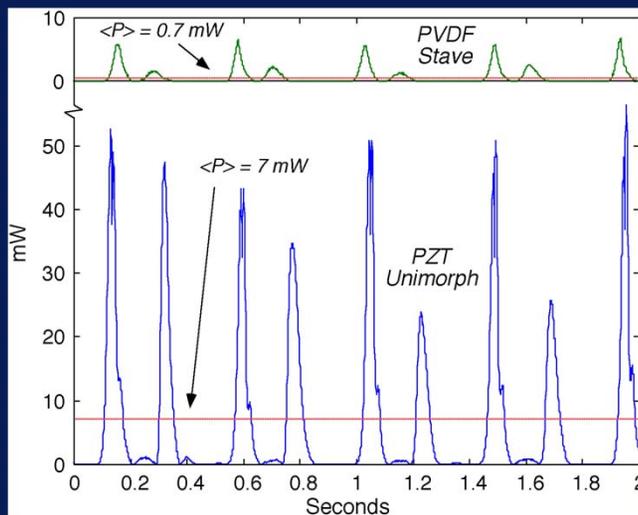
**PVDF Stave**  
*Molded into sole*  
*Energy from bend*

$$P_{\text{peak}} \cong 10 \text{ mW}$$
$$\langle P \rangle \cong 1 \text{ mW}$$

**“Thunder” PZT Clamshell Unimorph**

*Under insole*  
*Pressed by heel*

$$P_{\text{peak}} \cong 50 \text{ mW}$$
$$\langle P \rangle \cong 10 \text{ mW}$$

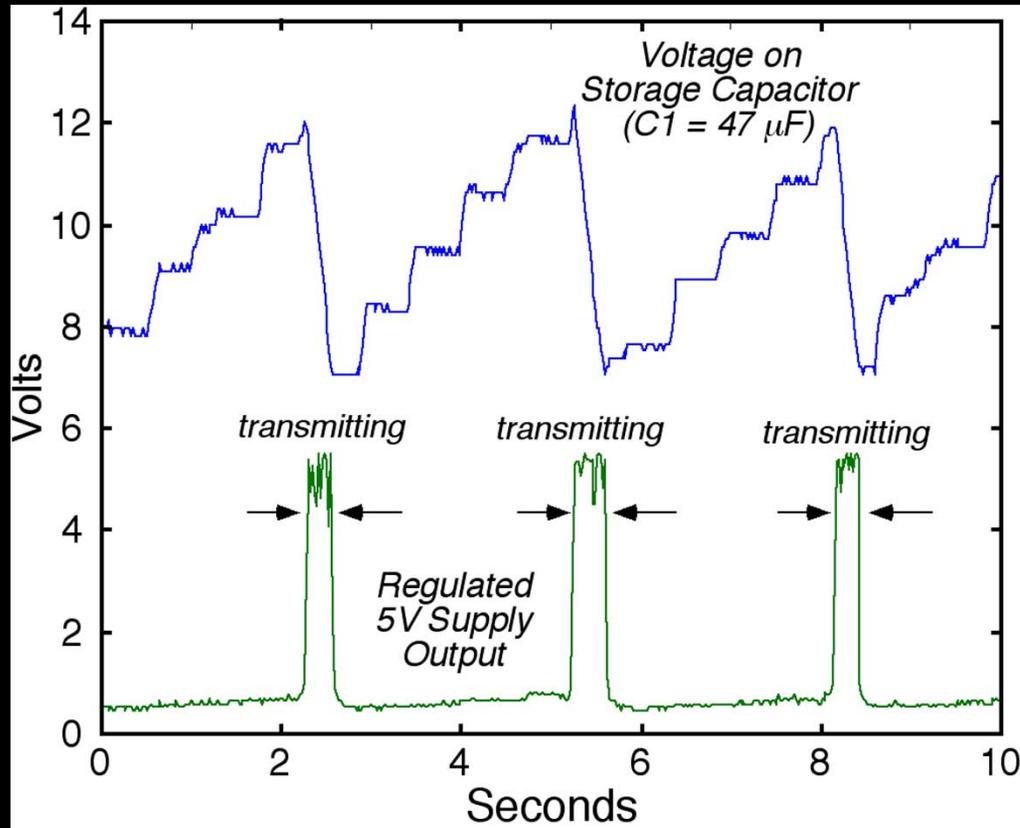


**Raw Power**  
*circa 1% efficient*  
*Unnoticeable*

*Responsive Environments Group*  
*MIT Media Lab*

*1998 IEEE Wearable Computing Conference*

# Application: Batteryless RF Tag



- Use Piezo-shoes to charge up capacitor after several steps
- When voltage surpasses 14 volts, activate 5 V regulator
  - Send 12-bit ID 6-7 times with 310 MHz ASK transmitter
- After 3-6 steps, we provide 3 mA for 0.5 sec
  - Capacitor back in charge mode after dropping below output

# Passive Hydraulic Chopping to Excite PZT at Resonance

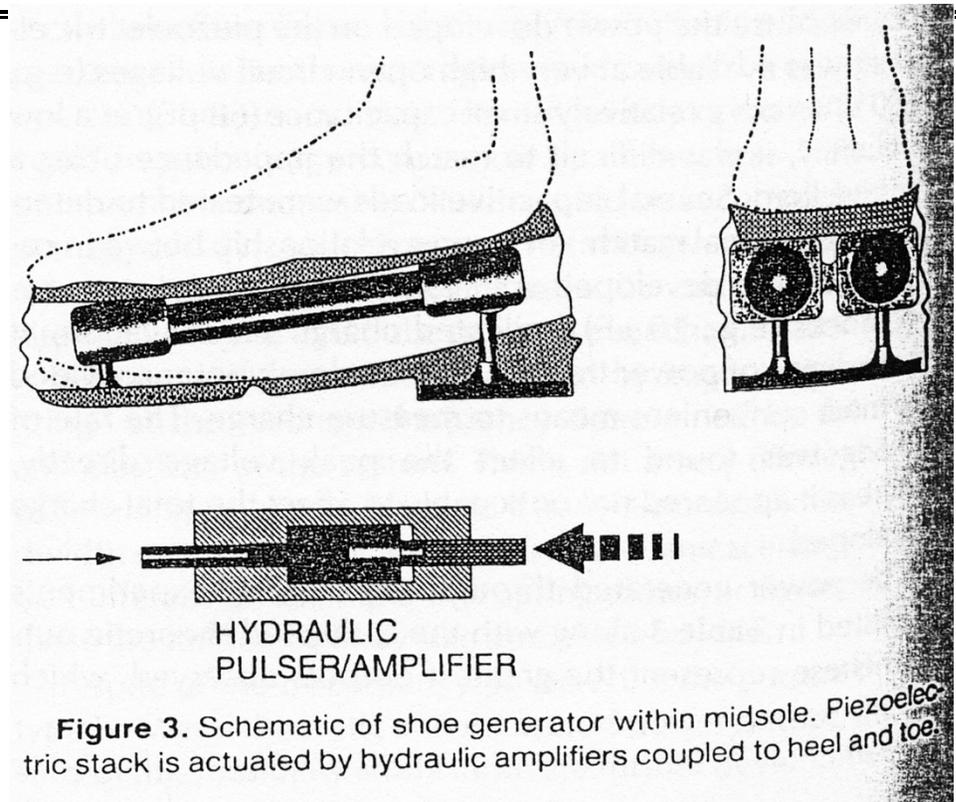
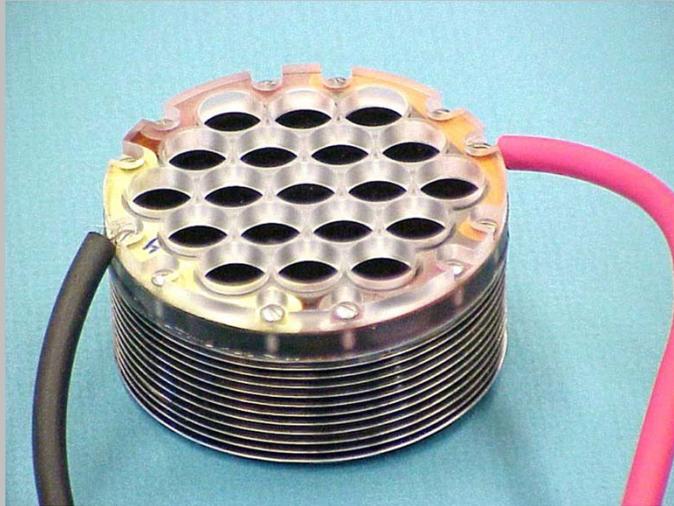


Figure 3. Schematic of shoe generator within midsole. Piezoelectric stack is actuated by hydraulic amplifiers coupled to heel and toe.

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- Antaki, et al., 1995
  - Passive hydraulic resonant excitation of piezoceramic stack during heel compression
  - Big, kludgy shoe
    - Developed to power artificial organs
    - Developed order of 0.2 – 0.7 Watt average power
    - 2 Watts from simulated “jogging”

# Dielectric Elastomers under the heel

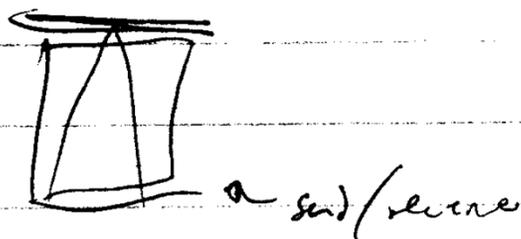
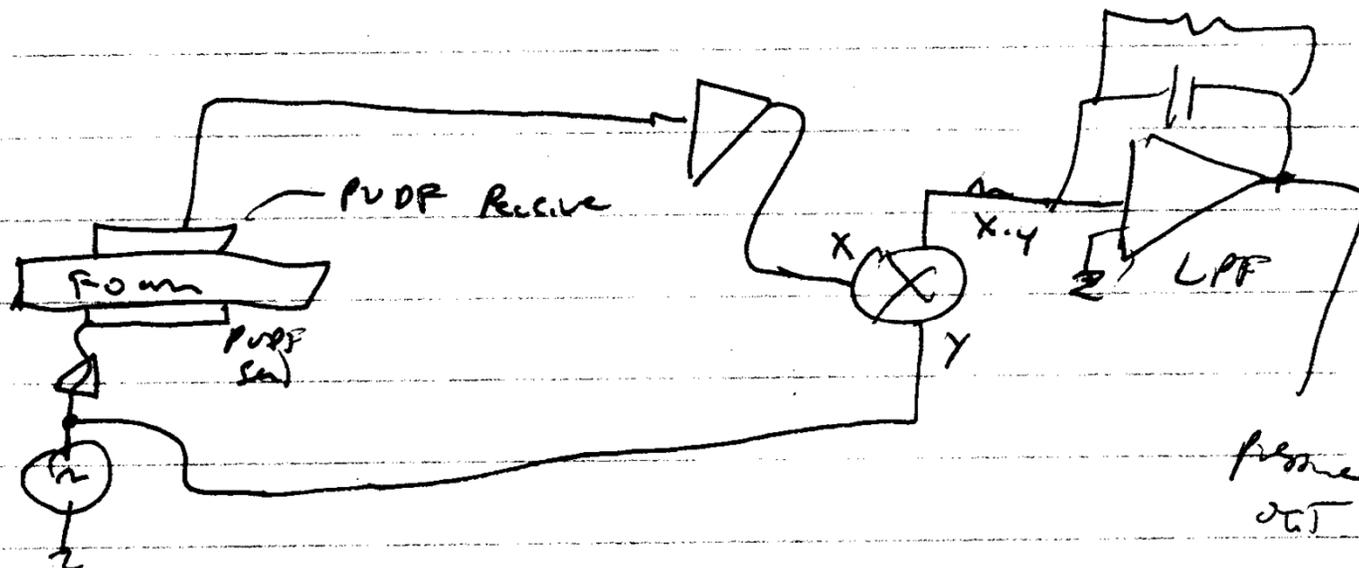


Courtesy of SRI International. Used with permission.

- Electrostatic generator with silicone rubber or flex acrylic elastomer between the plates
  - Placed under heel
  - 2-4 mm of squeeze gives 50-100% area strain
  - 4 kV across them!
  - Saw 0.8 Watt per shoe (2 Hz pace, 3 mm deflection)
  - Estimate that 1 Watt is possible with more deflection

*Ron Pelrine, Roy Kornbluh - SRI International*

# Driven Pressure Sensor



Electroactive Polymers

MIT OpenCourseWare  
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MAS.836 Sensor Technologies for Interactive Environments  
Spring 2011

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